

AIDA-2020

Advanced European Infrastructures for Detectors at Accelerators

Presentation

Advanced cooling: air cooling

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02 November 2015



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This work is part of AIDA-2020 Work Package **9: New support structures and micro-channel cooling.**

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Advanced cooling: air cooling and micro-channel cooling

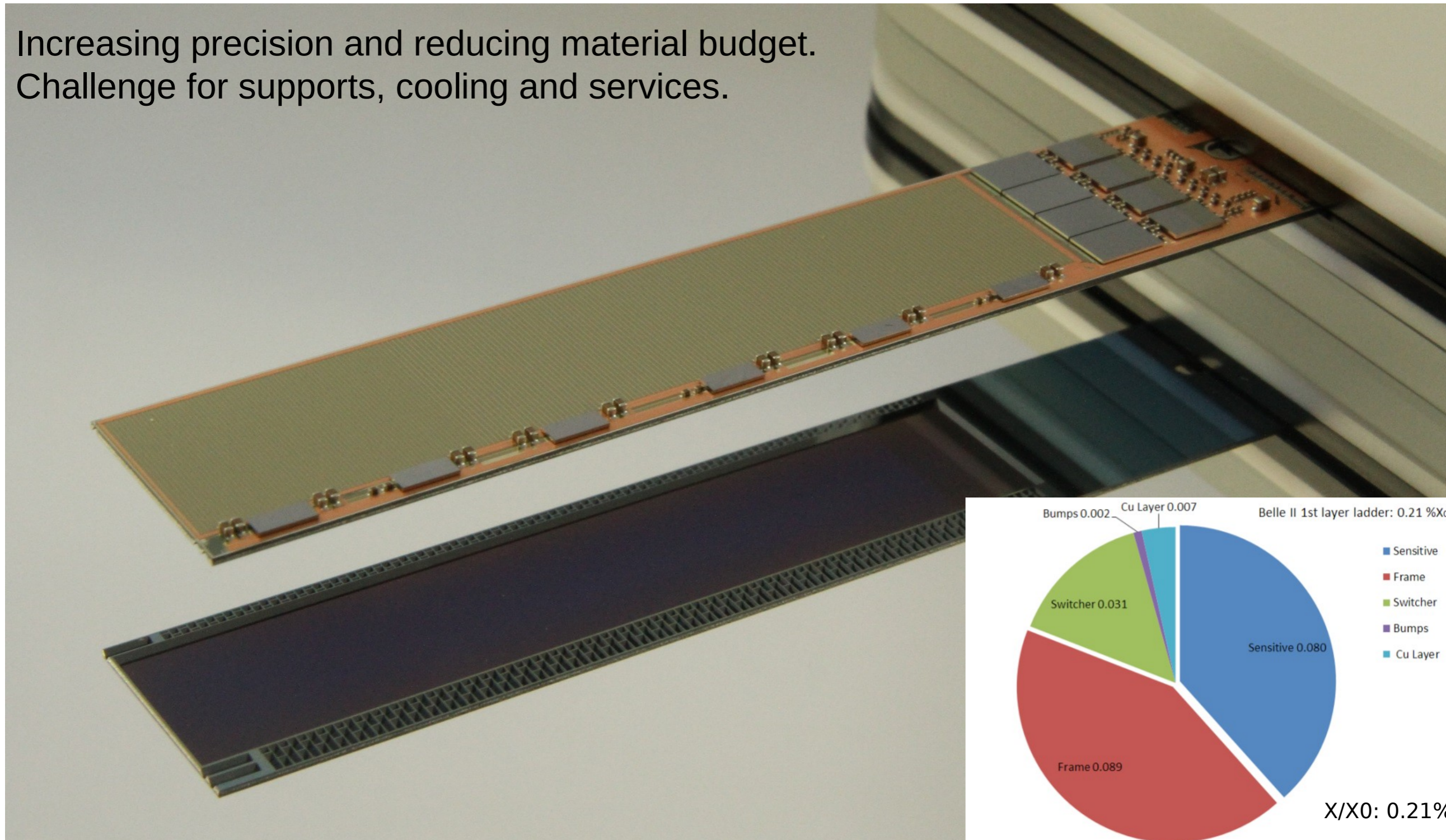
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C. Marinas², D. Markus², J. Ninkovic¹, M. Perelló³, E. Scheugenpflug¹, M.A. Villarejo³, M. Vos³*

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Thanks to AIDA H2020, CERN LCD

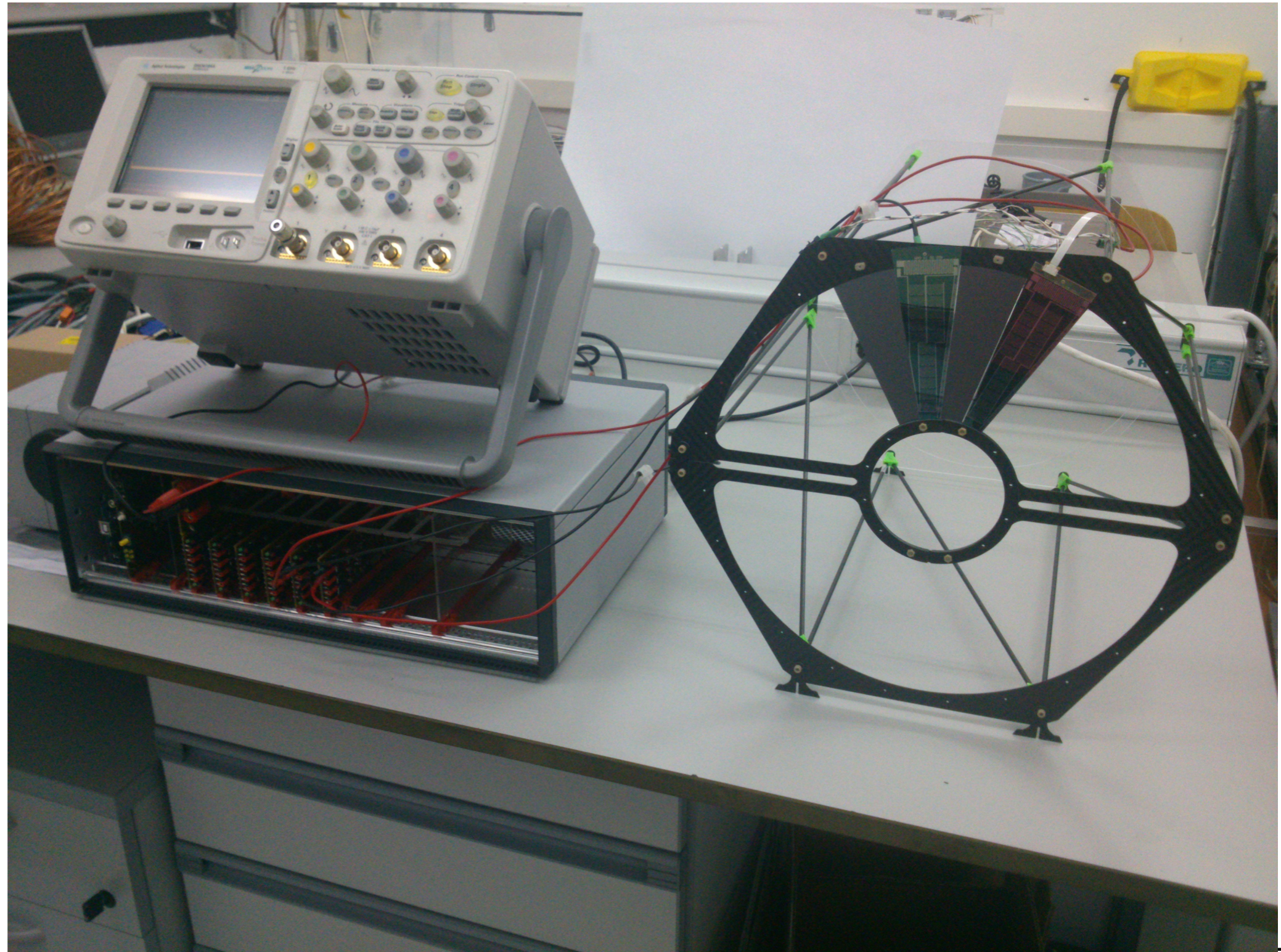
Ultra-thin and ultra-precise

Increasing precision and reducing material budget.
Challenge for supports, cooling and services.



Belle II Module 0. See also: DEPFET overview in this track

First generation mock-up



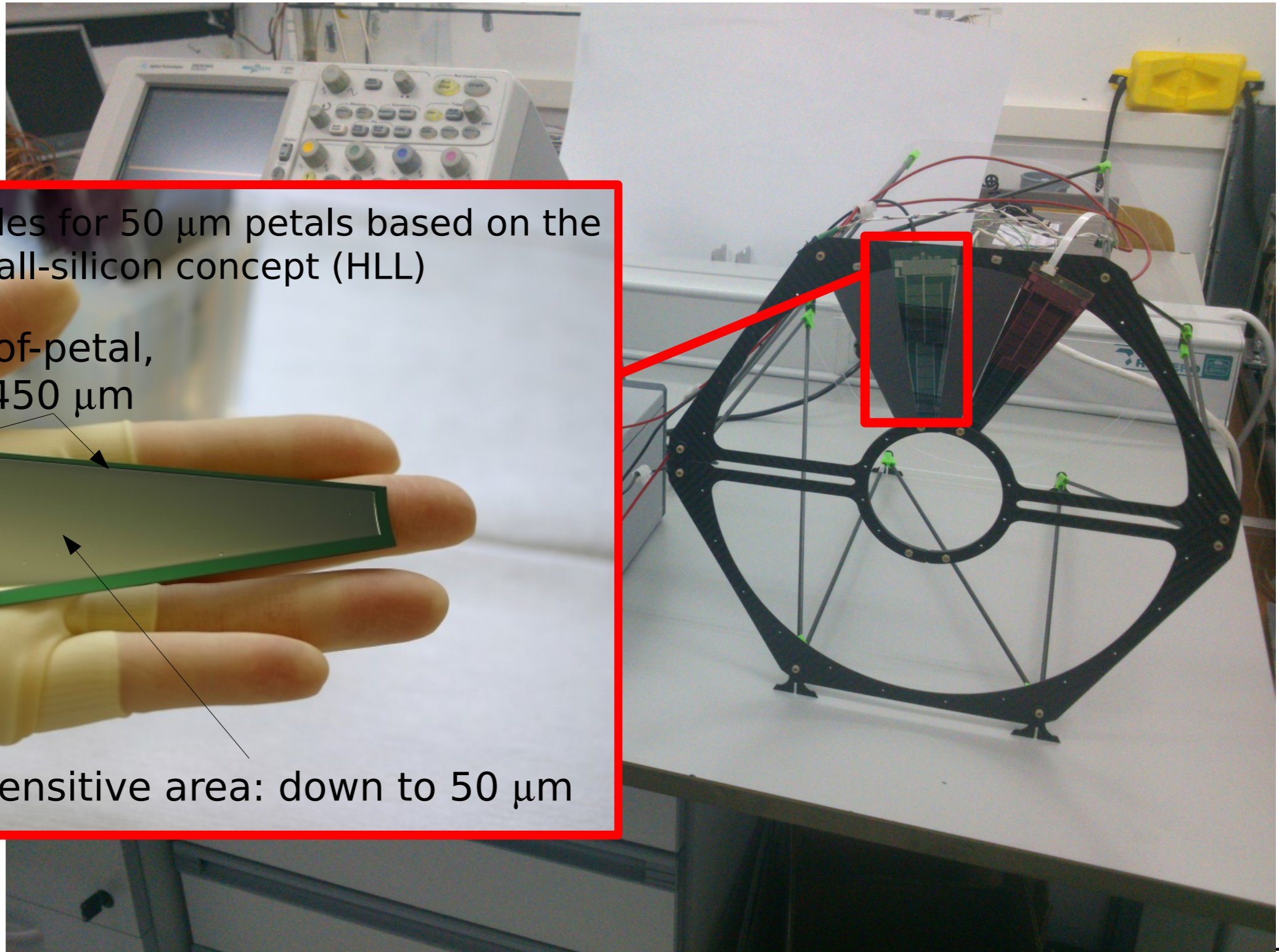
IFIC copy of the
AIDA pulsing
power supply

First generation mock-up

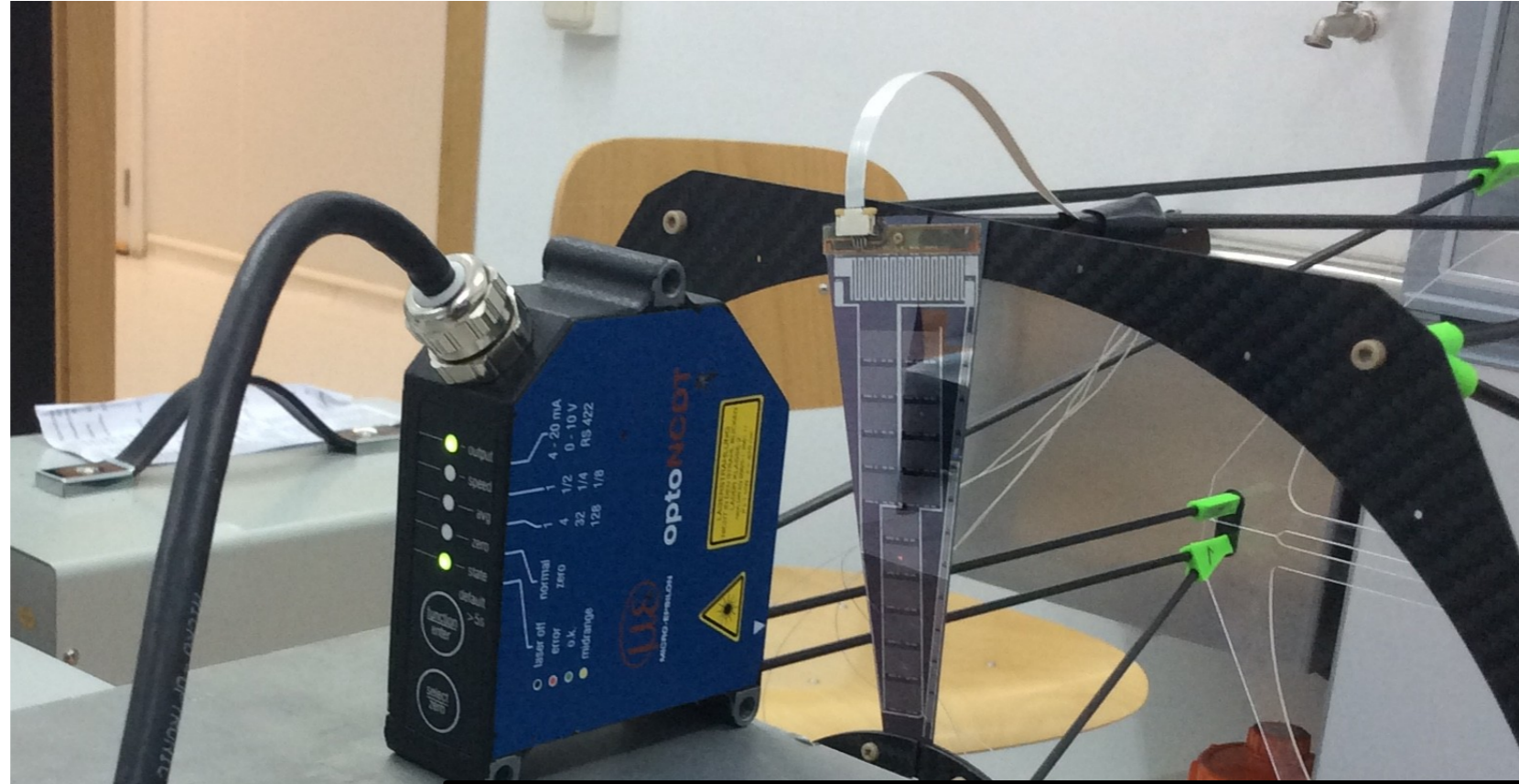
Mechanical samples for 50 μm petals based on the DEPFET all-silicon concept (HLL)

Frame, end-of-petal, balcony: $\sim 450 \mu\text{m}$

Ultra-thin sensitive area: down to 50 μm

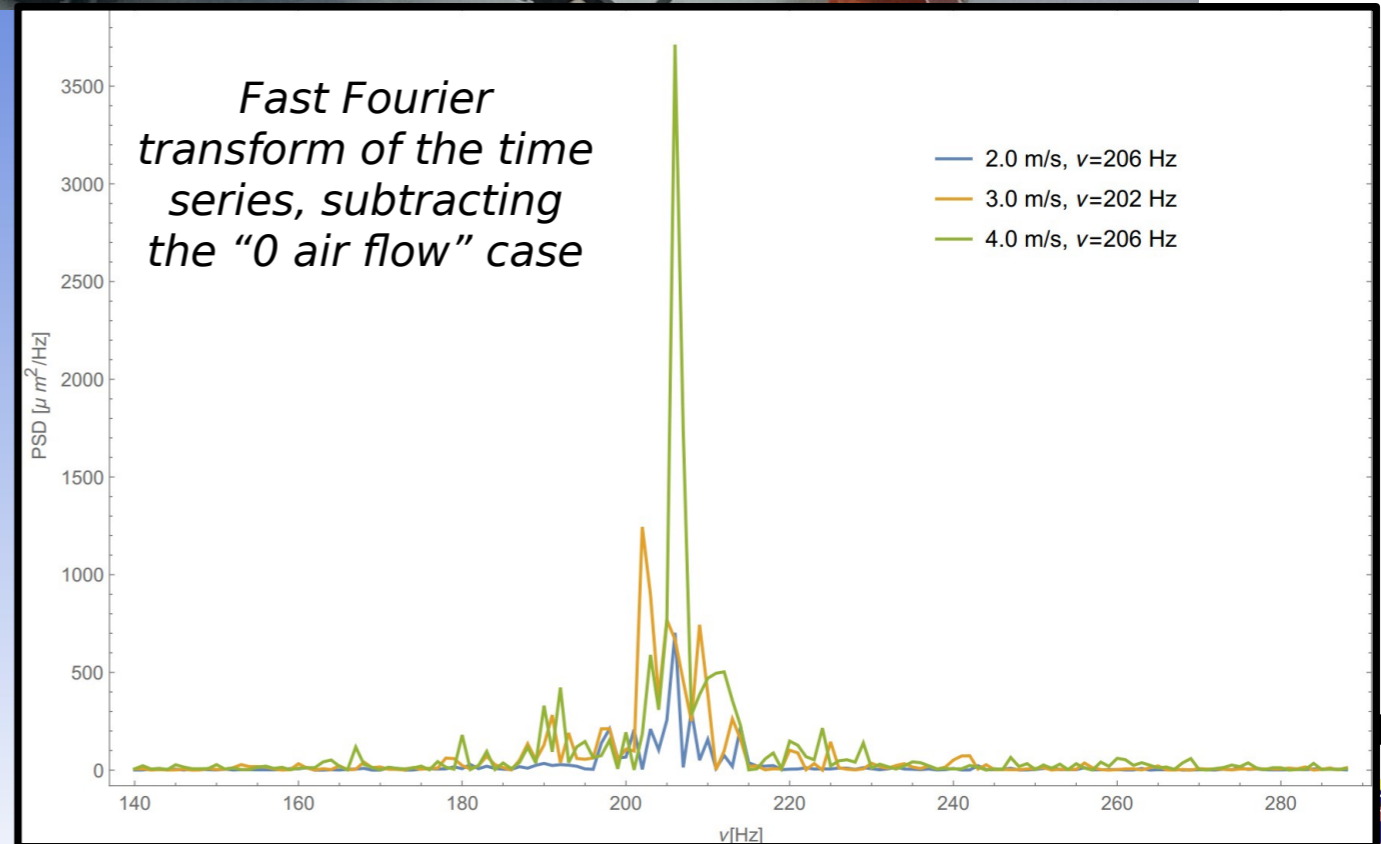
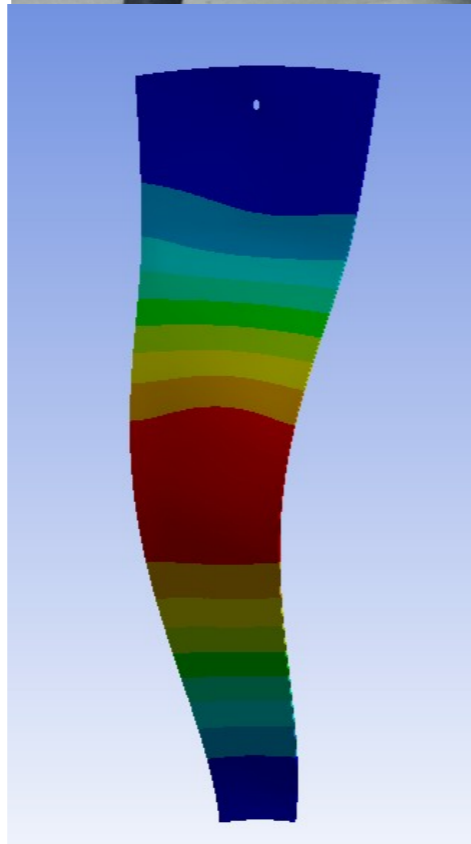


Air flow & deformation



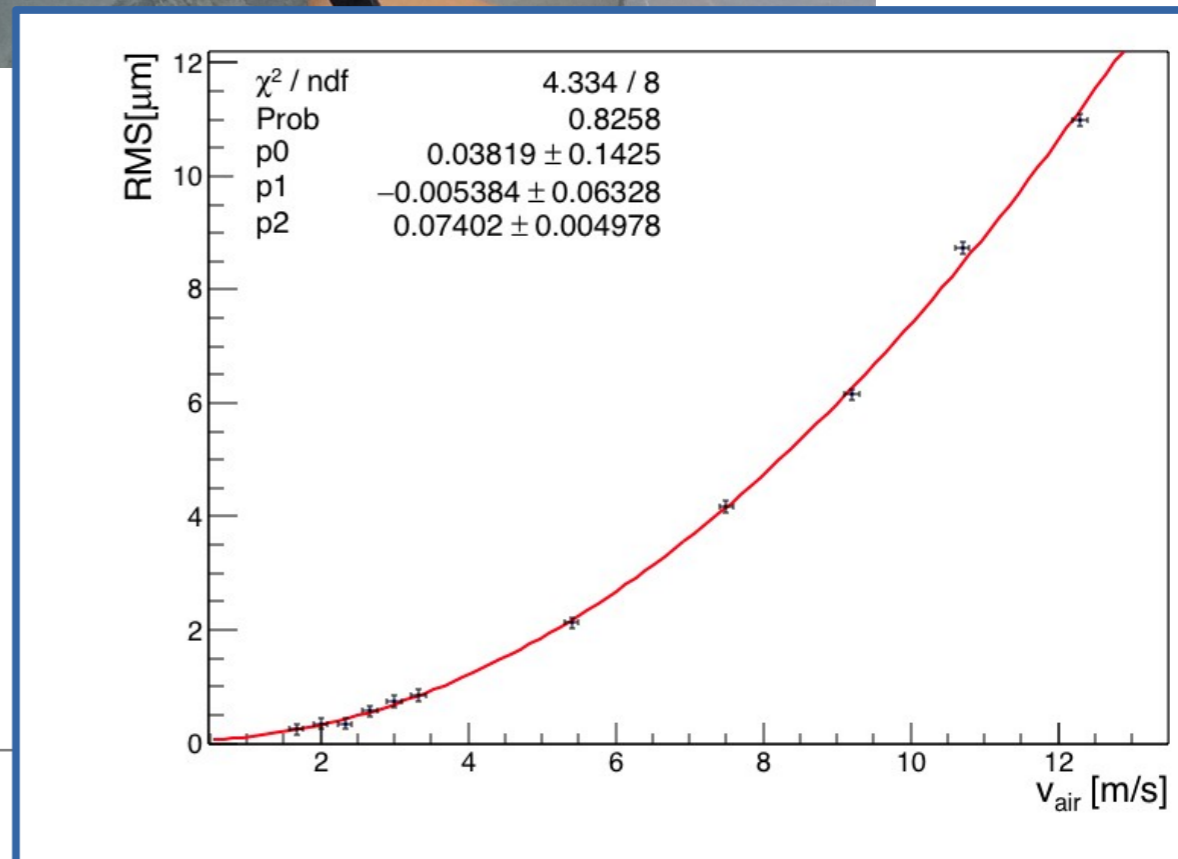
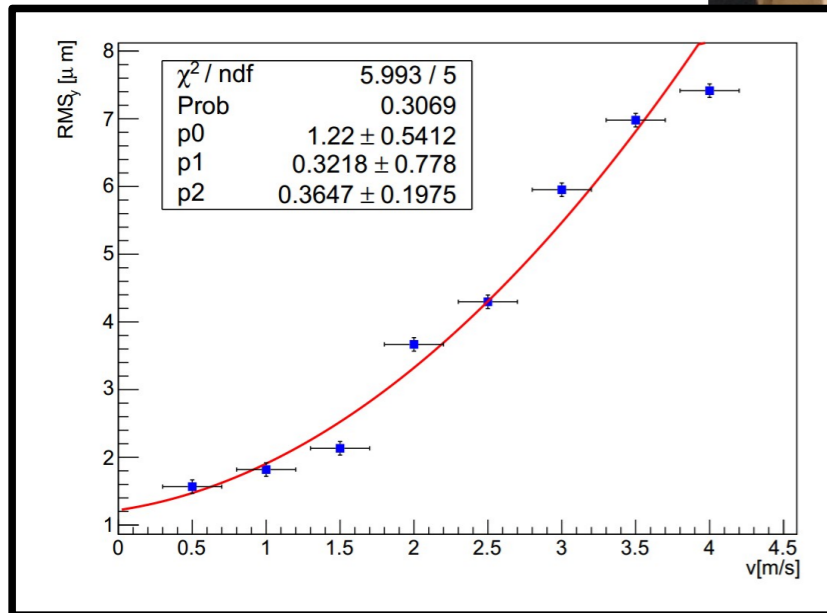
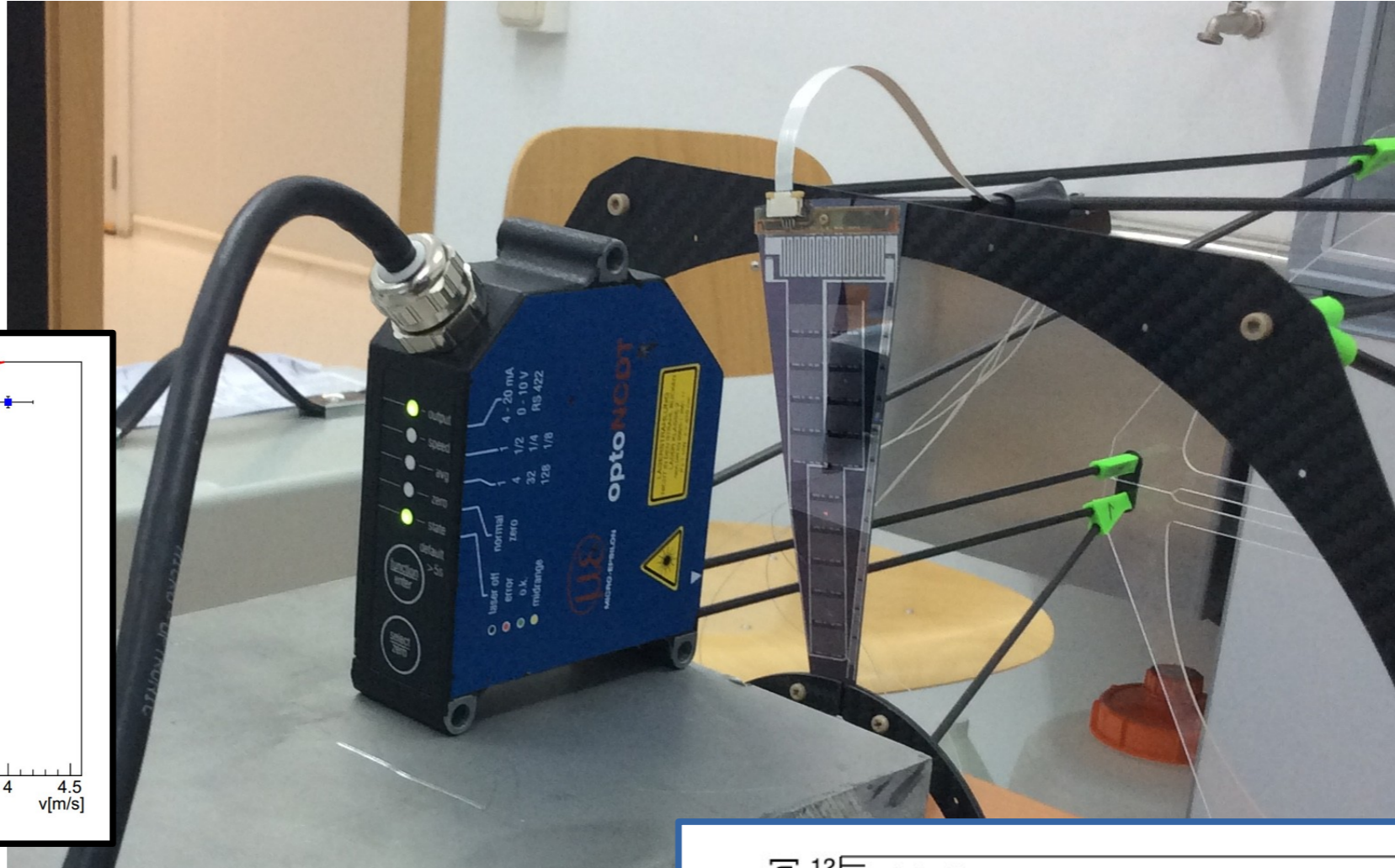
Vibrations induced by air are at 200 Hz. Finite-element simulation of just the petal predict 300 Hz.

Work on petal design and CF support to raise the lowest eigenfrequency



Air flow & deformation

IFIC measurements



Air flow does introduce slight vibrations. For large air speed these become sizeable wrt the intrinsic resolution.

CERN LCD "wind tunnel"



LC thermo-mechanics of thin sensors

Thermo-mechanical performance of silicon sensors studied with thinned mechanical samples

Study of power pulsing & air cooling very encouraging:

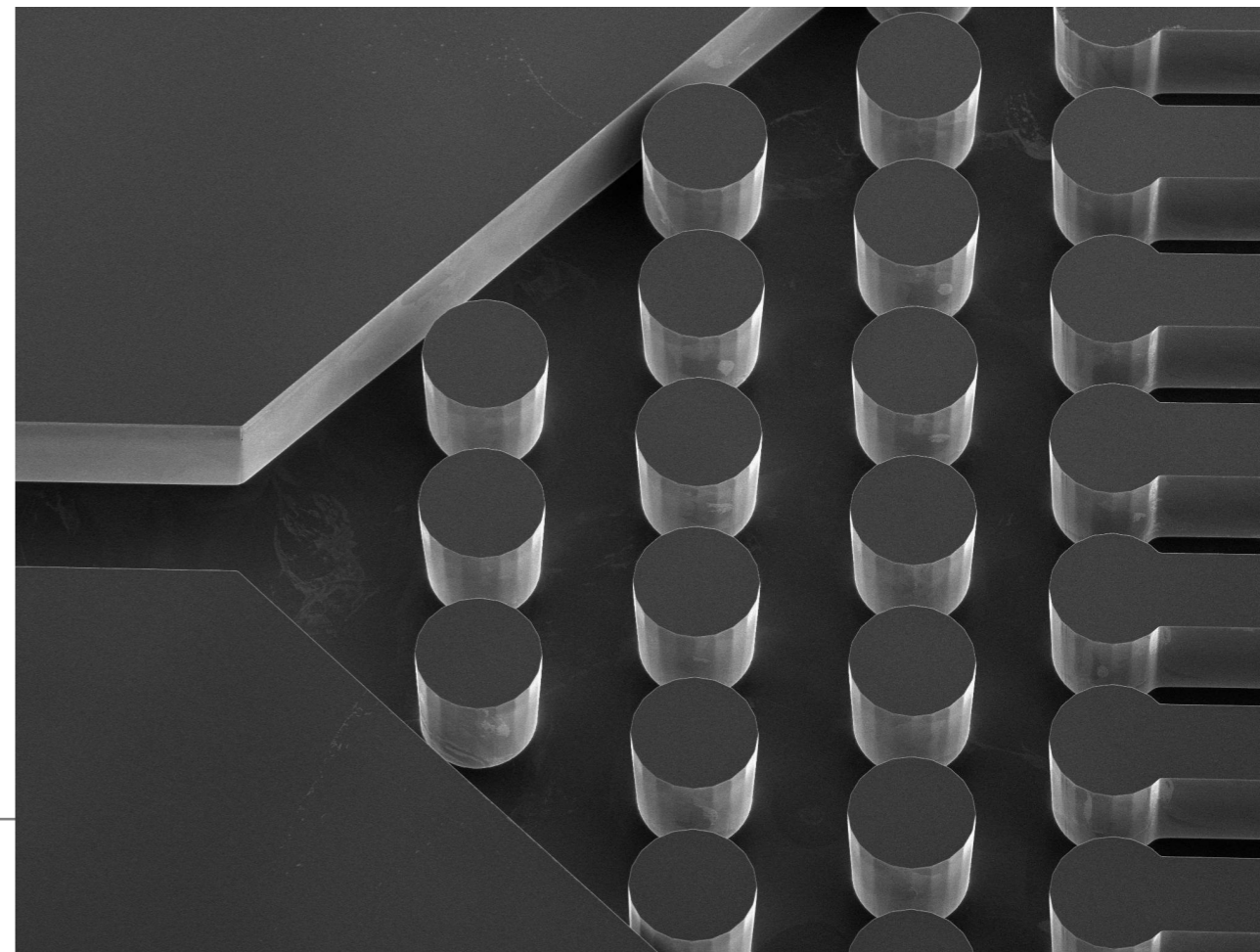
- Power pulsing has no impact on mechanical stability (but still without B-field!)
- A laminar air flow in front of the disk, with a moderate speed of 1m/s, is sufficient to remove the nominal DEPFET heat load (assuming 1/25 duty cycle for power pulsing, IEEE TNS 60-2-2, arXiv:1212.2160)
- Air flow of greater than “a few m/s” must be avoided

The challenge is to bring in the air and establish a gentle, laminar air flow



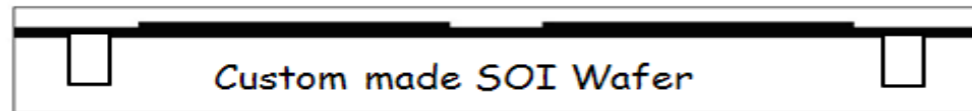
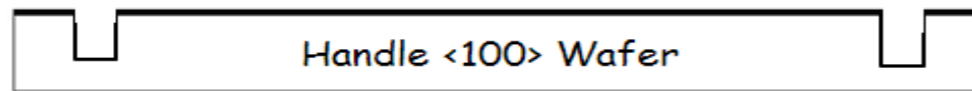
Micro-channel cooling, our take...

- Liquid cooling provides excellent temperature control, but is too bulky
 - Industry is exploring micro-channel cooling (and, to some extent, high energy physics; LHCb, NA62, ALICE)
 - DEPFET, with localized power dissipation and SOI process, provides an interesting application → integrate cooling in all-silicon ladder
 - Compared to existing effort, aim at relatively high temperature, low pressure
 - Keep it simple: mono-phase
-
- Small team at University of Bonn
MPG-HLL Munich and IFIC Valencia
 - Embedded in larger effort AIDA2020
(P. Petagna CERN)



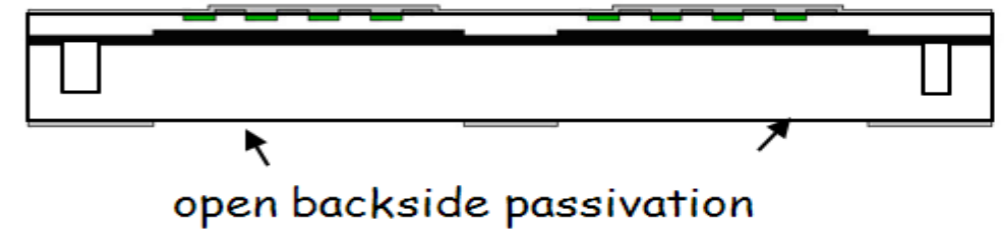
All-silicon ladder with integrated cooling

a) oxidation and back side implant of top wafer



b) wafer bonding and grinding/polishing of top wafer

c) process → passivation

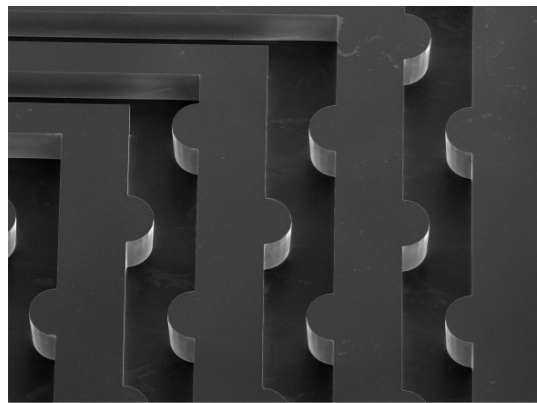
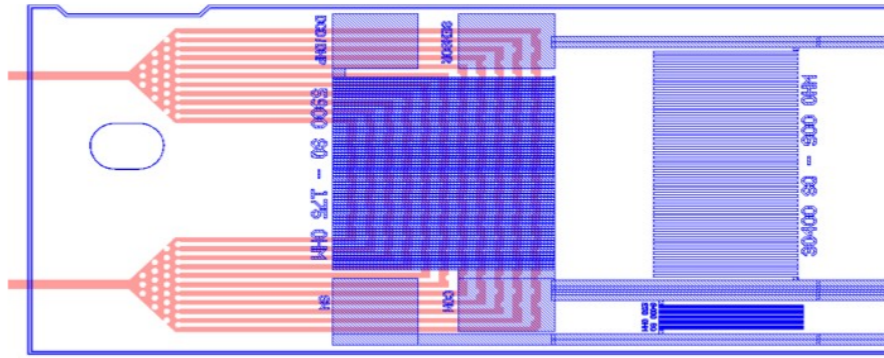


d) anisotropic deep etching opens "windows" in handle wafer

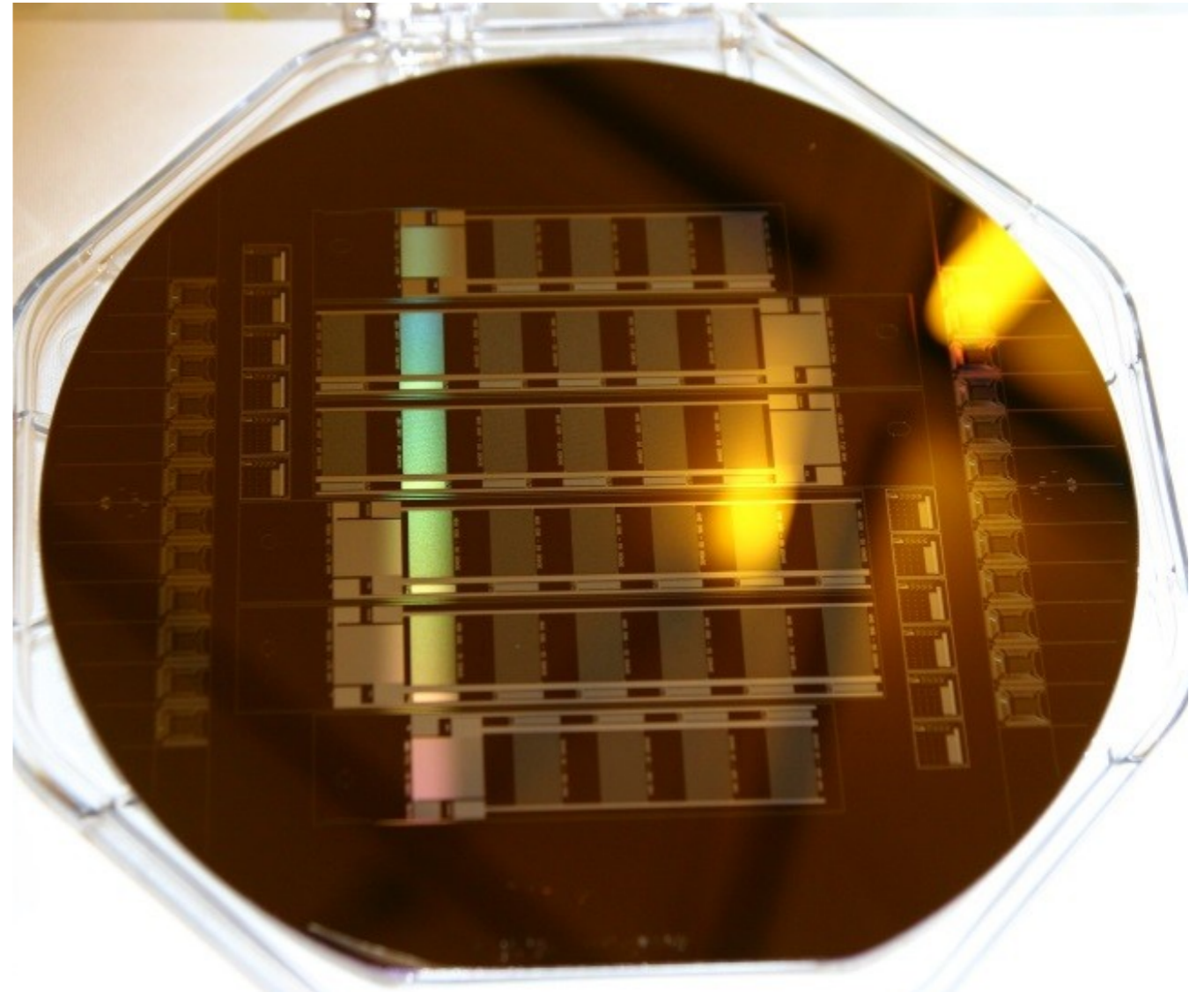
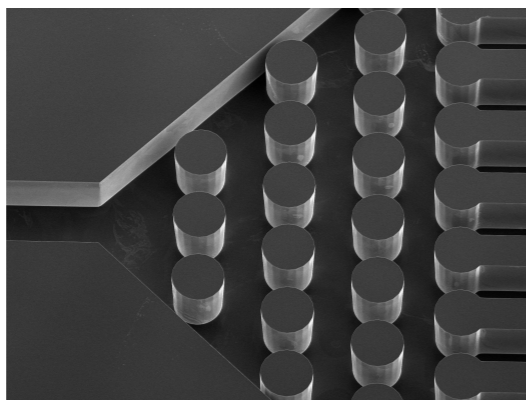
thinned all-silicon module with integrated cooling channels

- integrate channels into handle wafer beneath the ASICs
- channels etched before wafer bonding → cavity SOI (C-SOI)
- full processing on C-SOI, thinning of sensitive area
- micro-channels accessible only after cutting (laser)

MCC prototypes



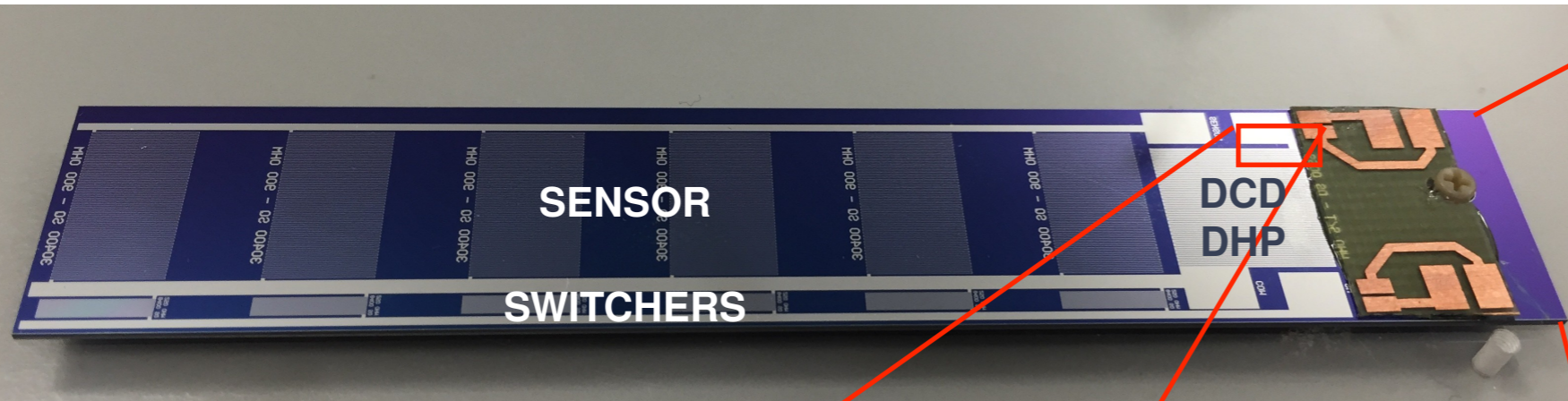
Micro-channel
pattern in
handle wafer



6 ladders with integrated
MCC manifolds on a wafer



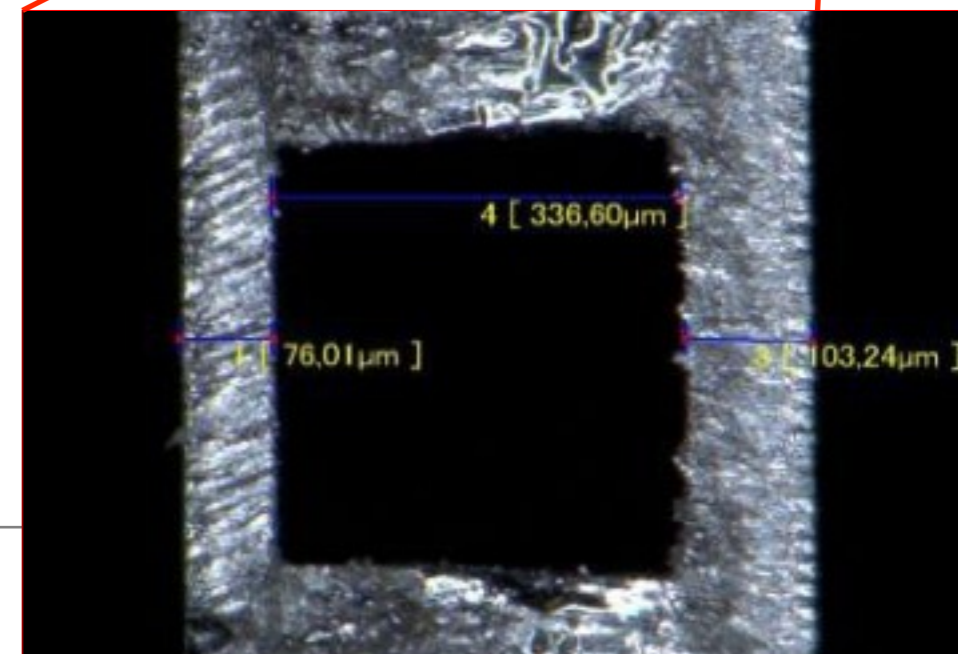
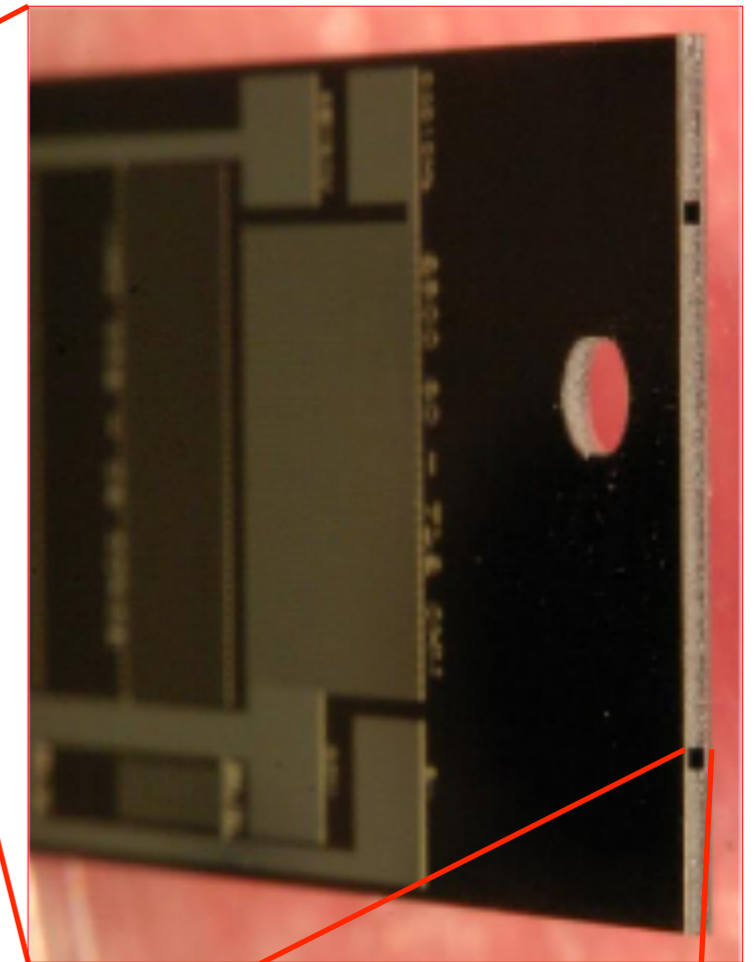
All-silicon ladder with integrated cooling



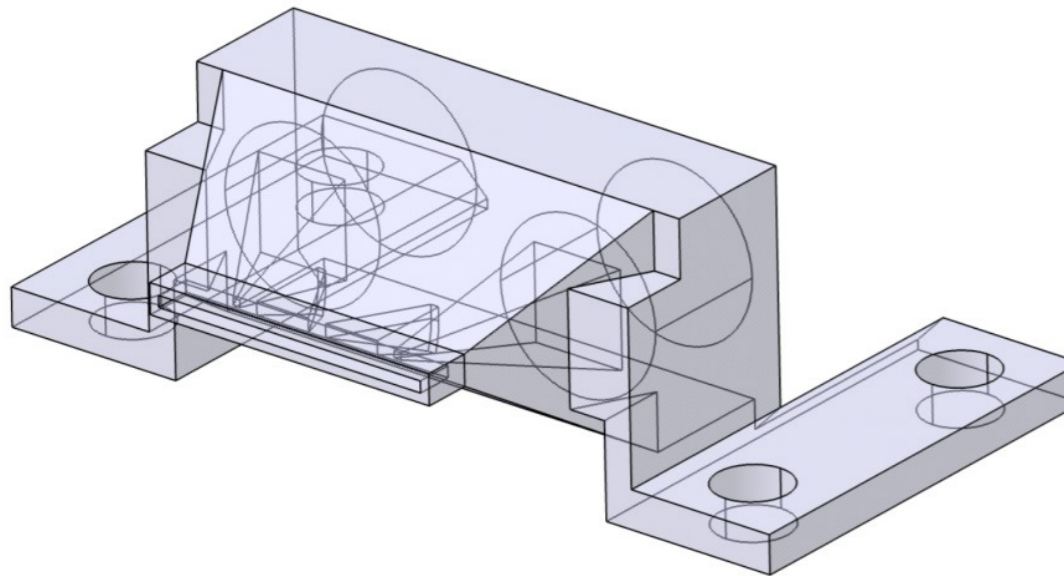
Resistor circuits to mimic DEPFET power dissipation

Thermo-mechanical half-ladder for the LC inner vertex detector

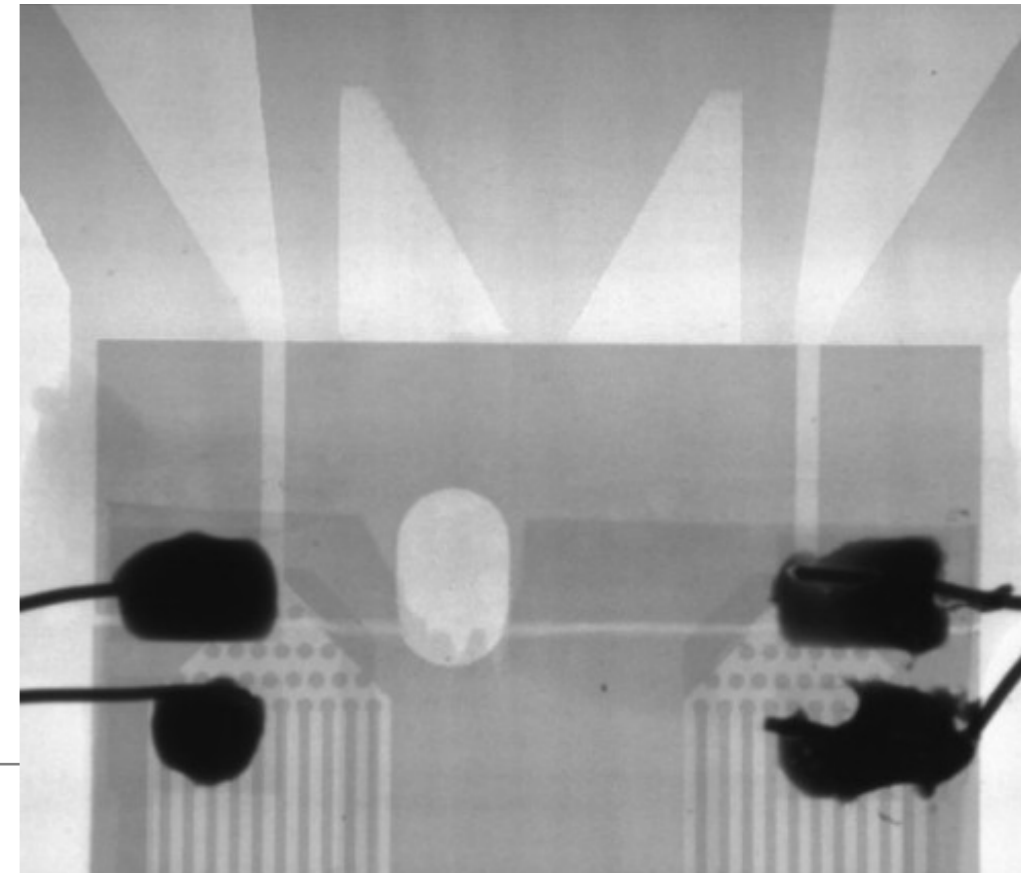
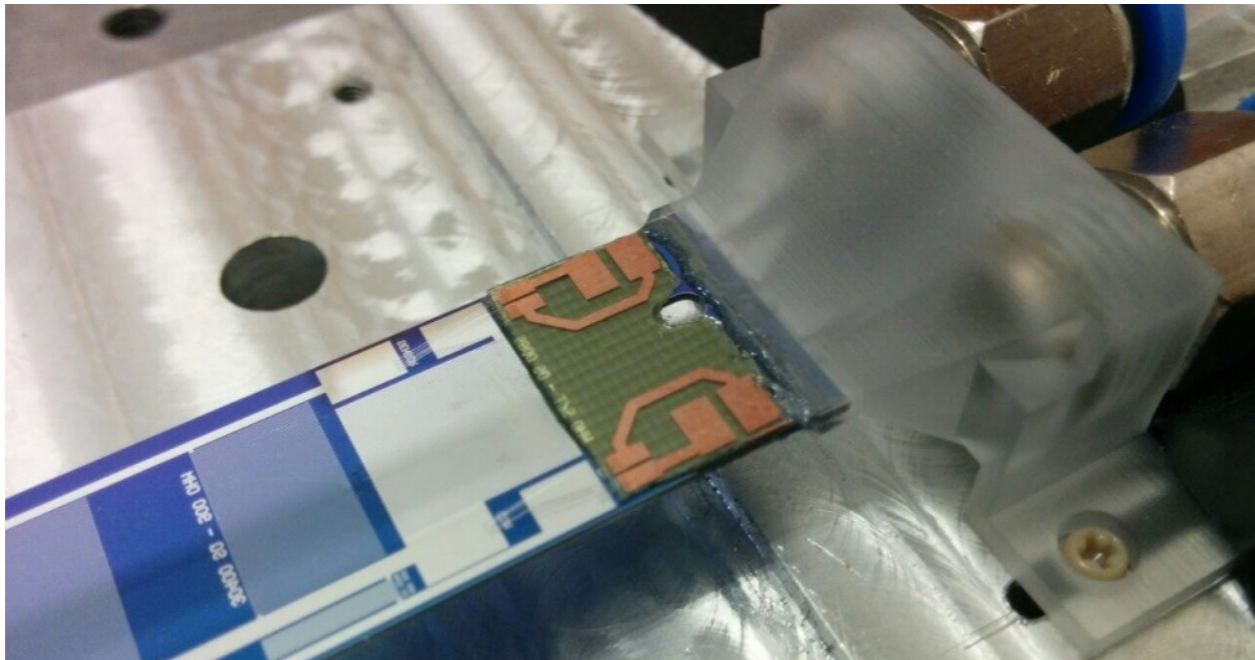
Inlet and outlet visible after wafer cutting



The interconnect challenge

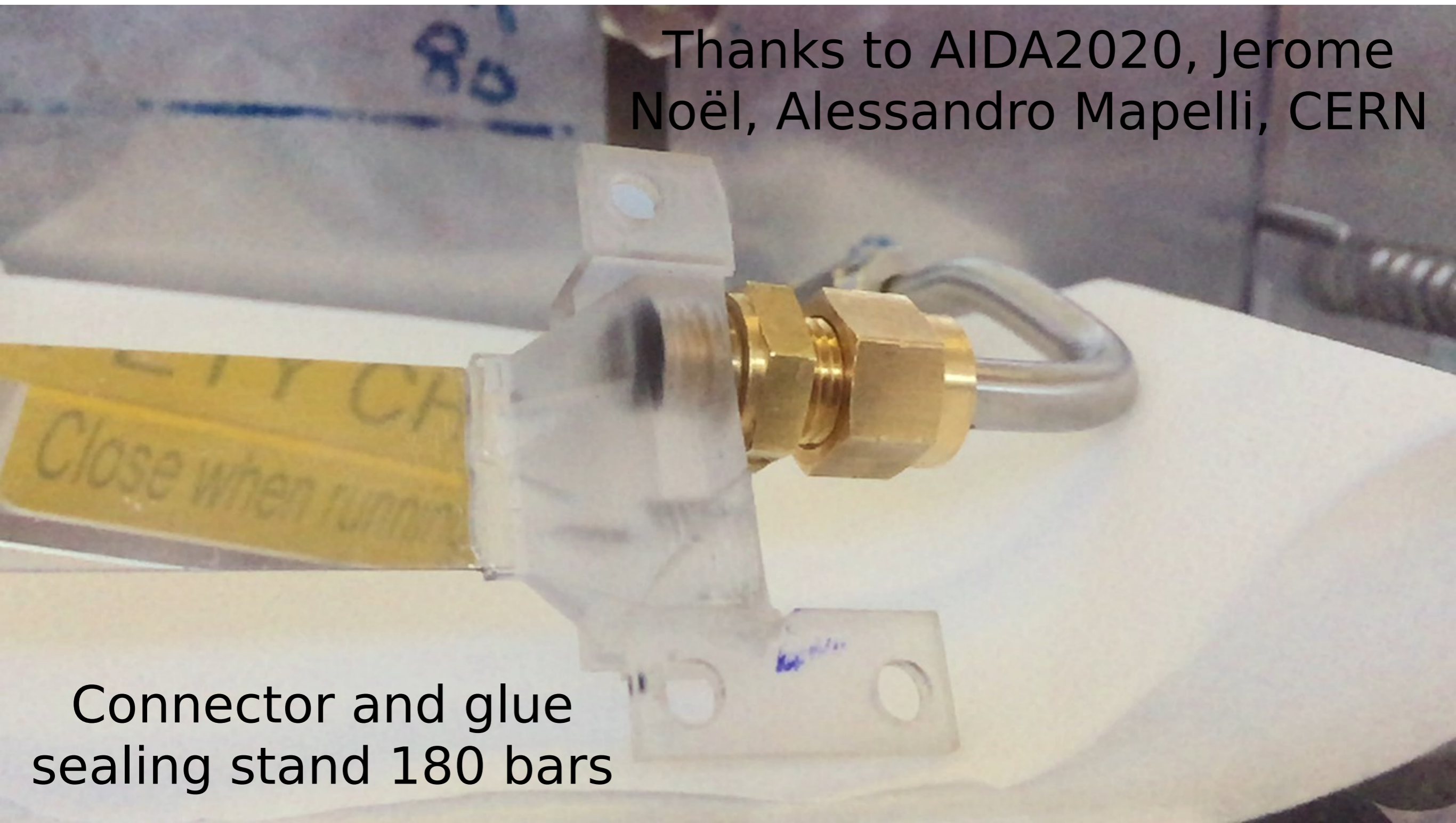


- ▷ Laboratory connector
= interface to high-pressure Swagelok
- ▷ 3D-printed (stereo-lithography)
15 μm precision \rightarrow self-aligning
- ▷ Sealed with glue (Araldite)



Pressure test

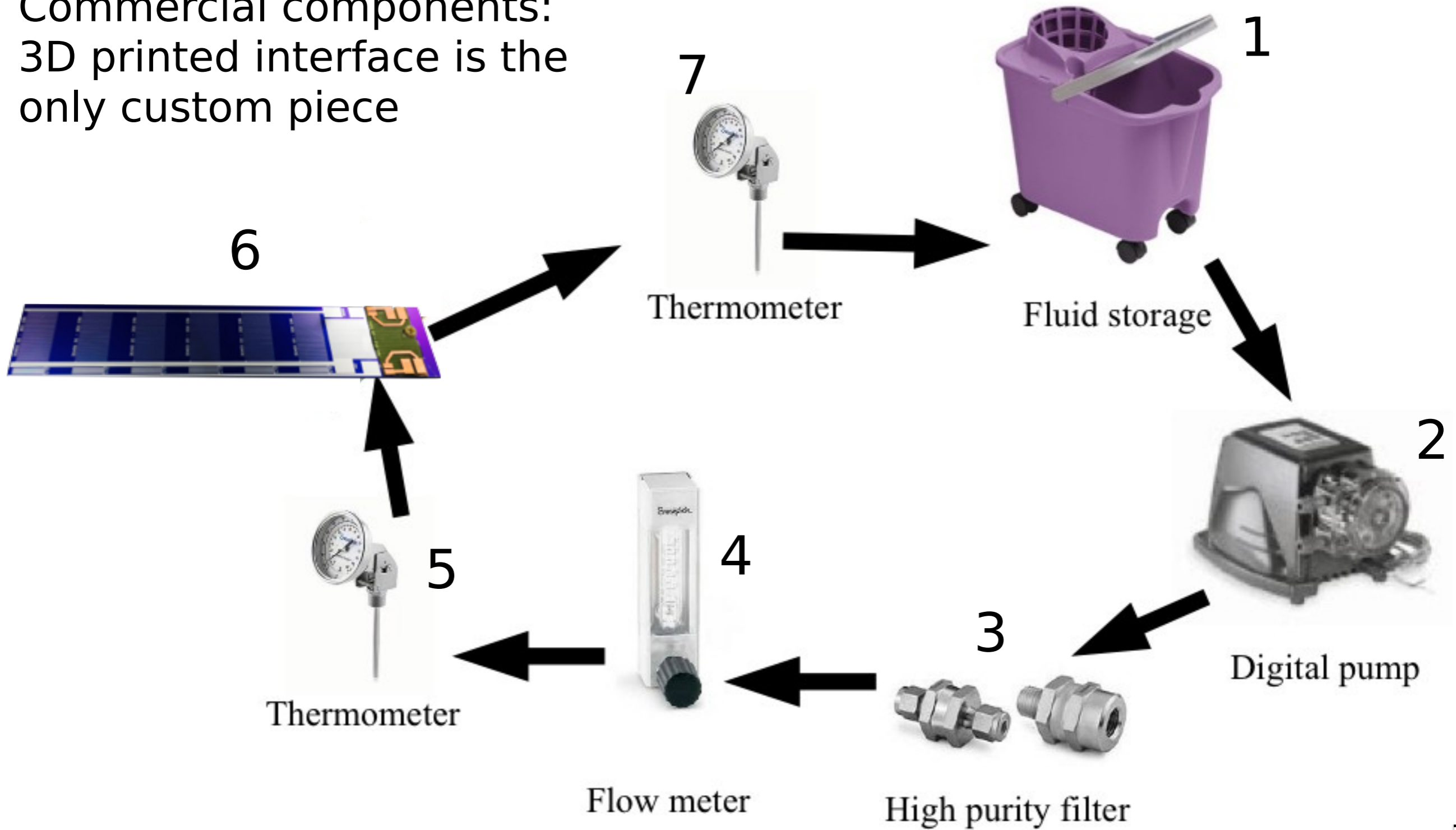
Thanks to AIDA2020, Jerome Noël, Alessandro Mapelli, CERN



Connector and glue sealing stand 180 bars

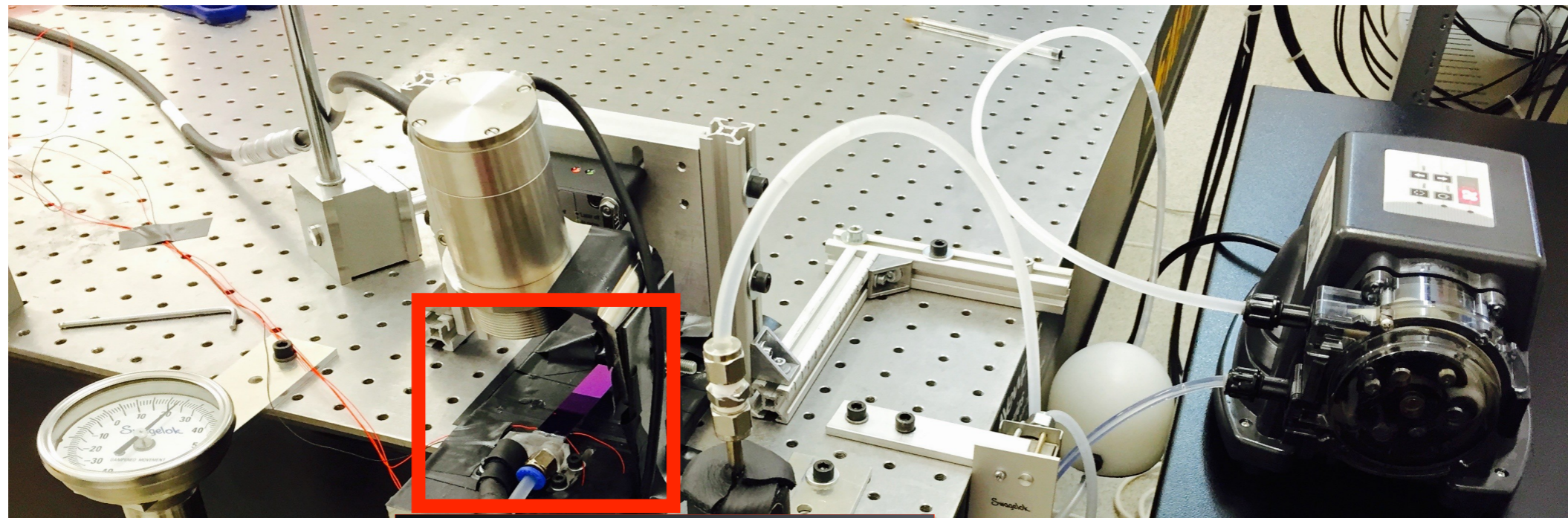
Experimental setup

Commercial components:
3D printed interface is the
only custom piece

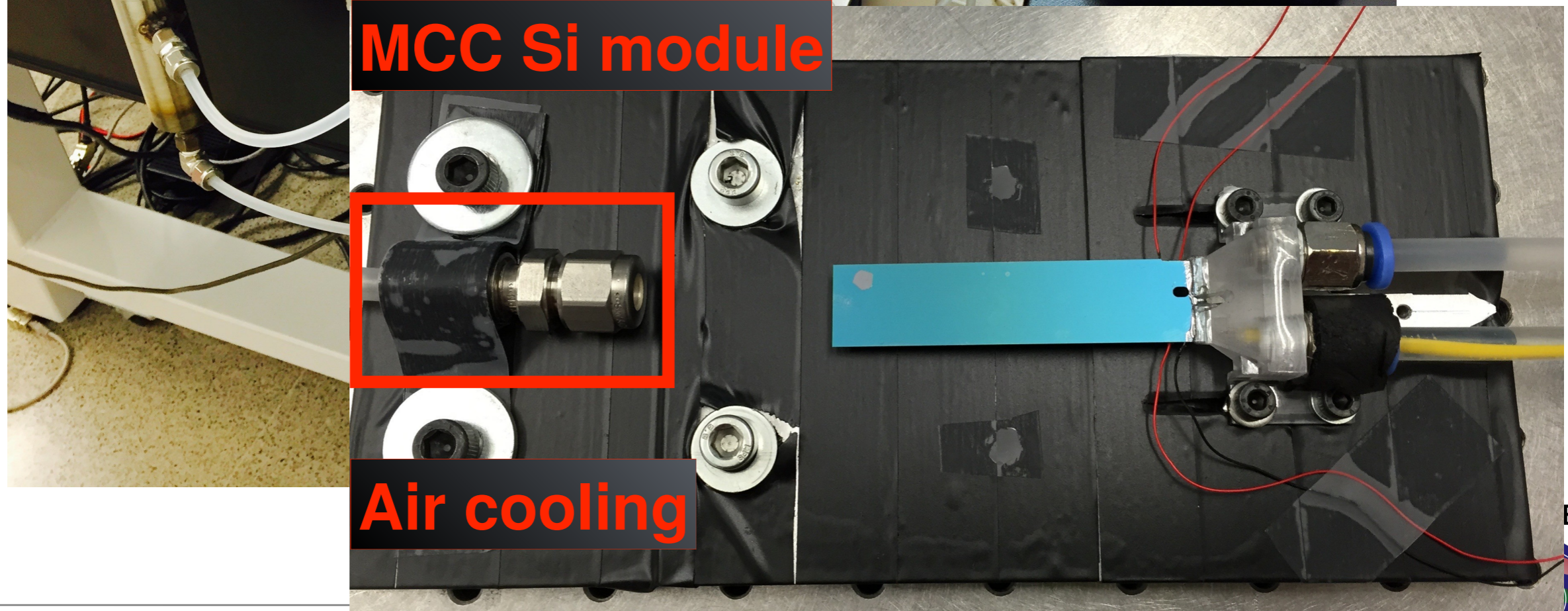


Experimental setup

For operation above 0°C **mono-phase liquid cooling** with (H₂O)



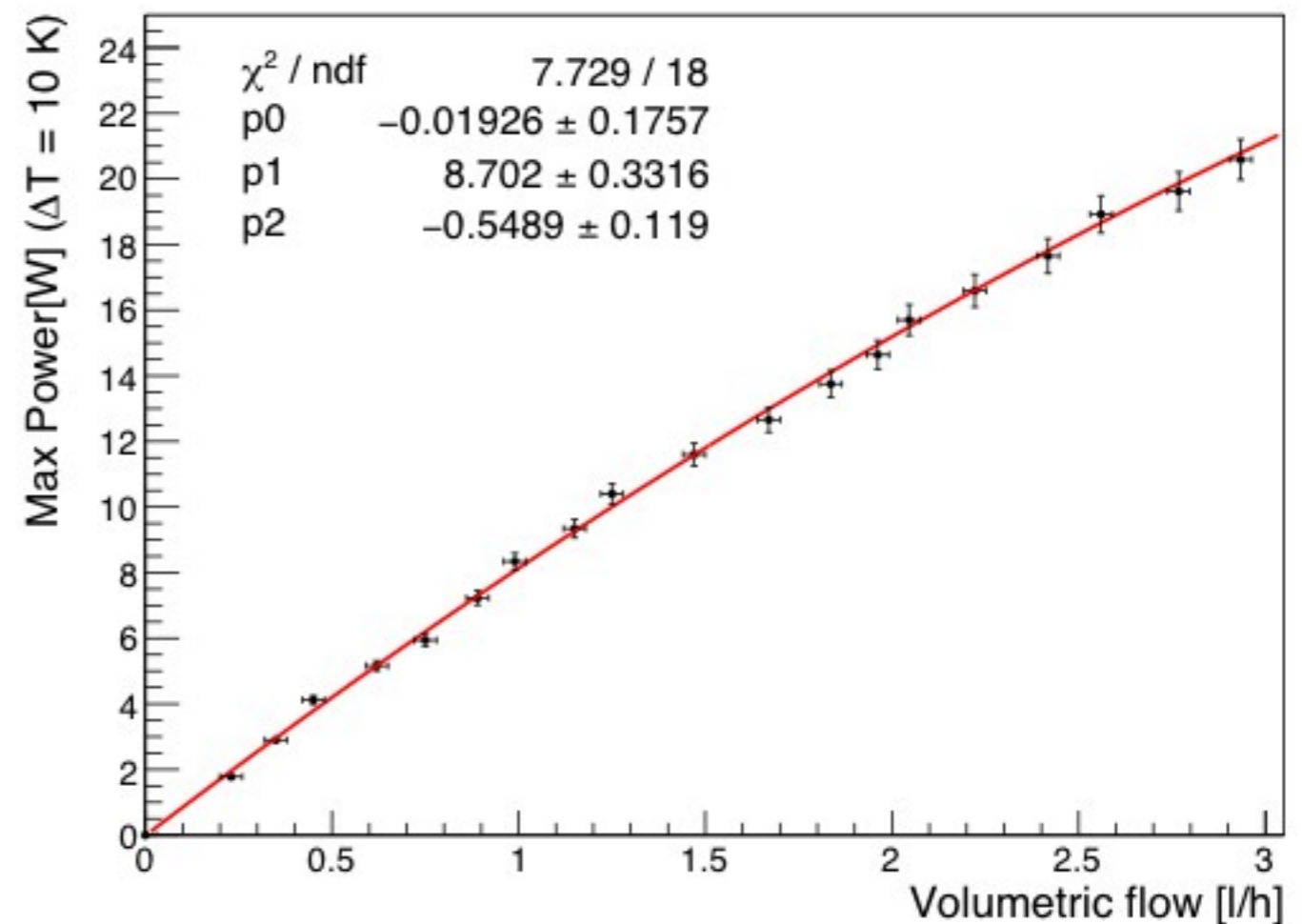
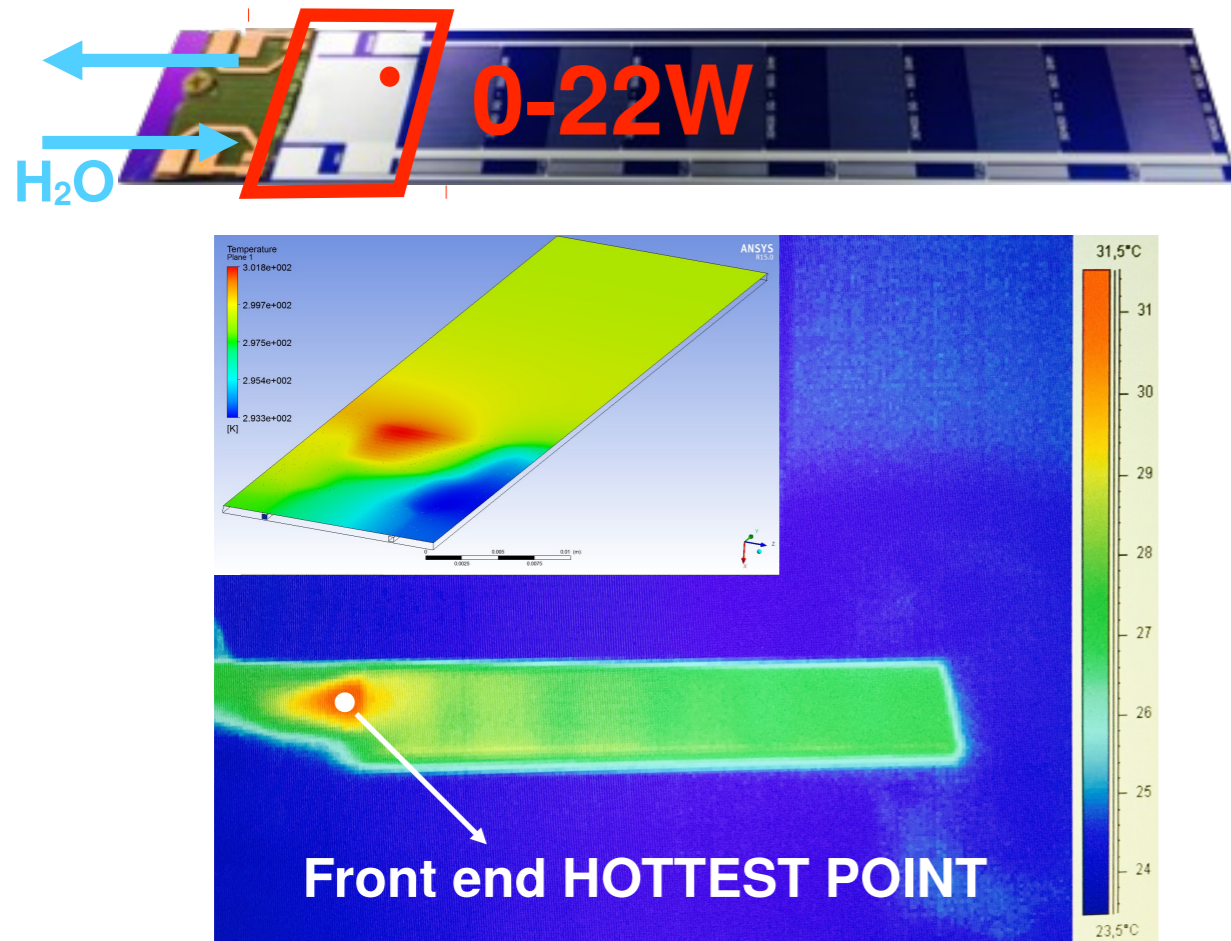
MCC Si module



Air cooling



Thermal measurements: Maximum Power vs Volumetric flow

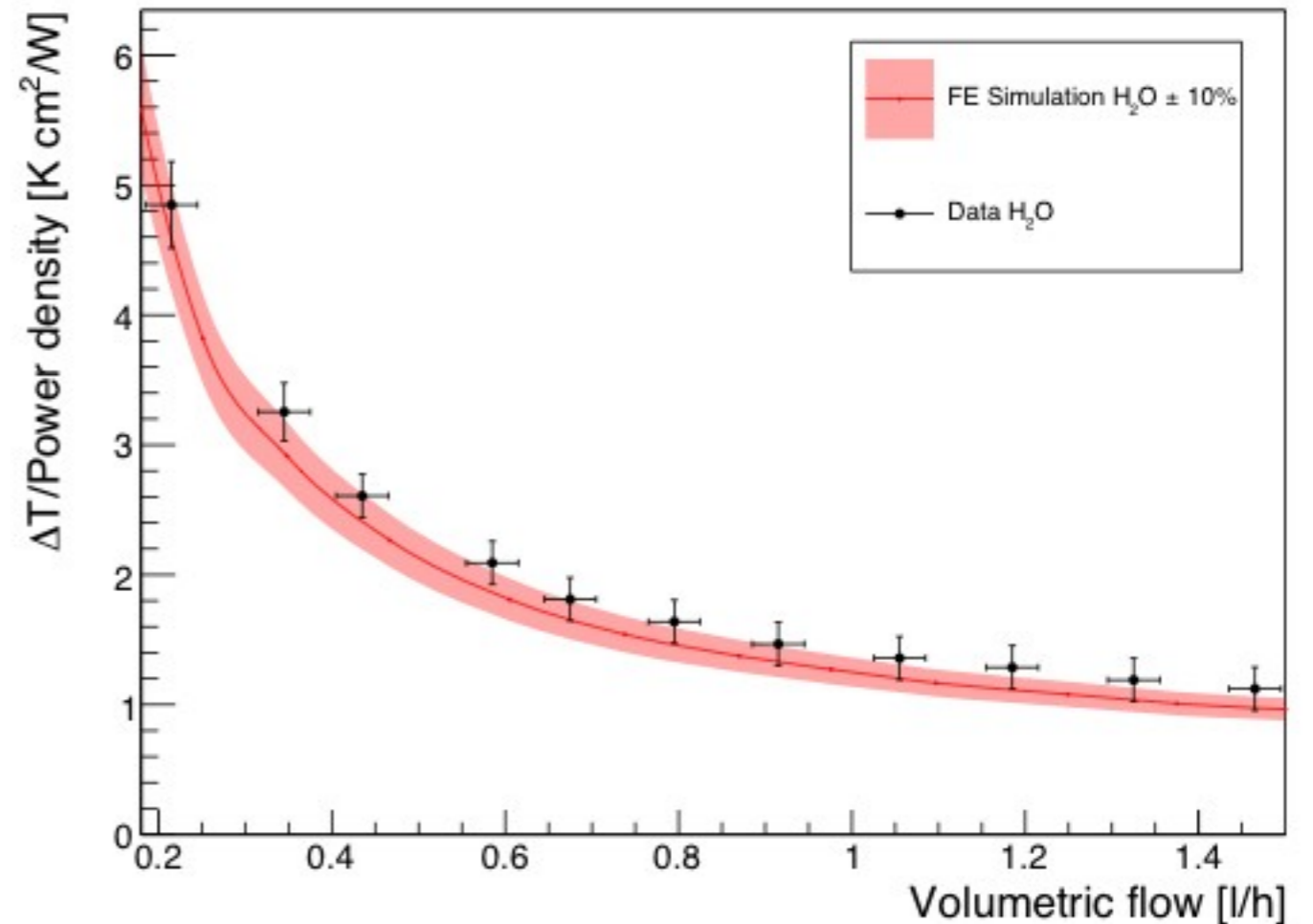
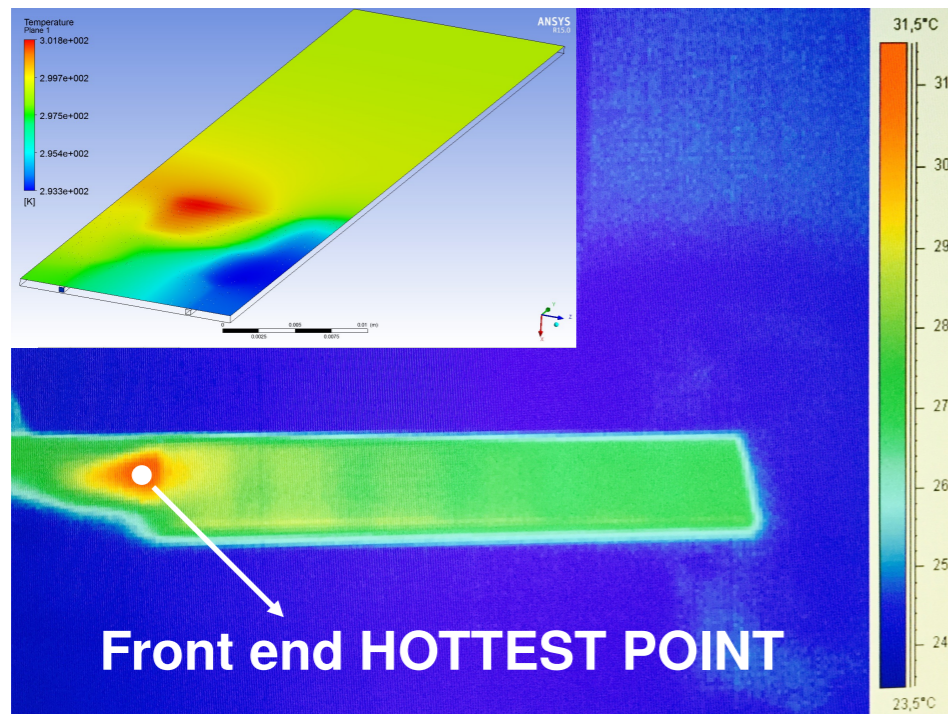


Maximum power supported for a ΔT of 10 °C as a function of the volumetric flow

- **Temperature stable** even with power density of **25 W/cm²**
- **Power vs vol. flow** at max. pump power (~ 3 l/h)
- **Low pressure** needed: 0.2 - 1.5 bar

Extremely powerful: MCC removes many times the instantaneous with very small temperature gradient

Thermal measurements: MCC

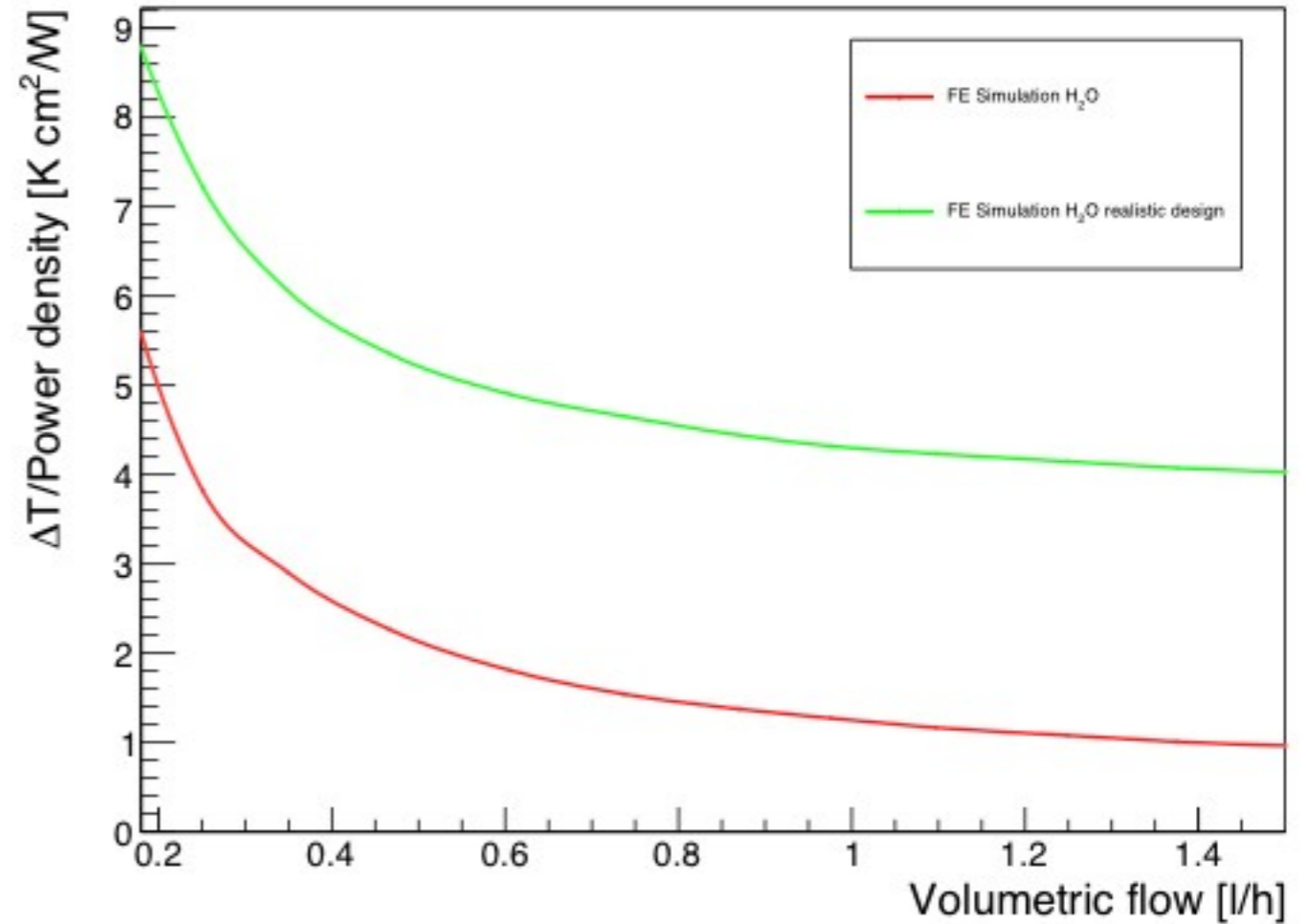
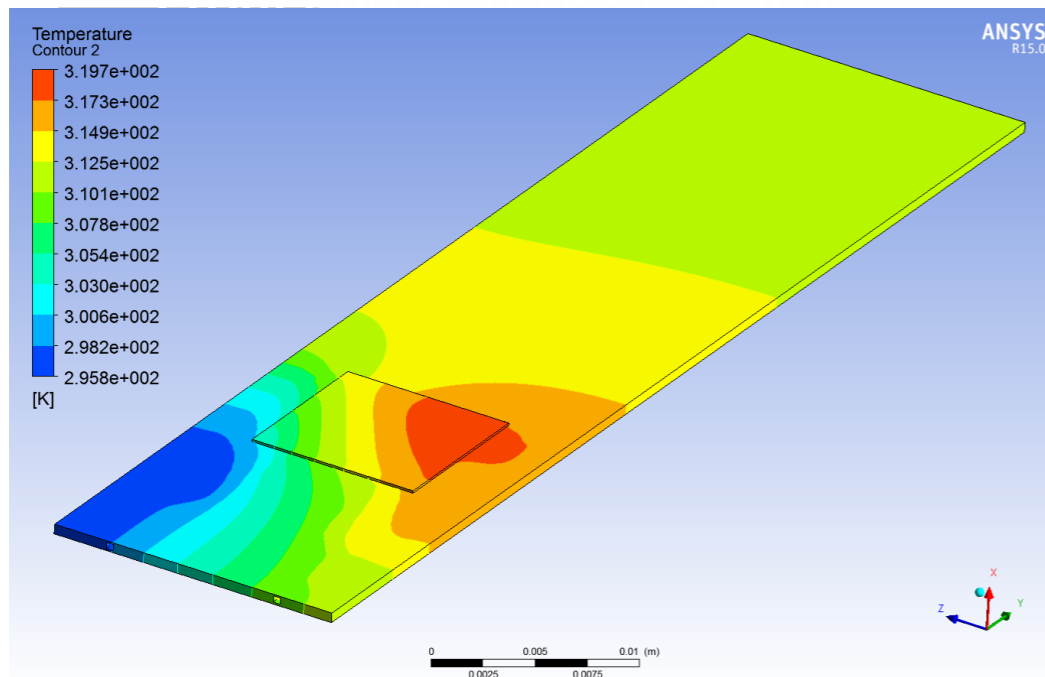
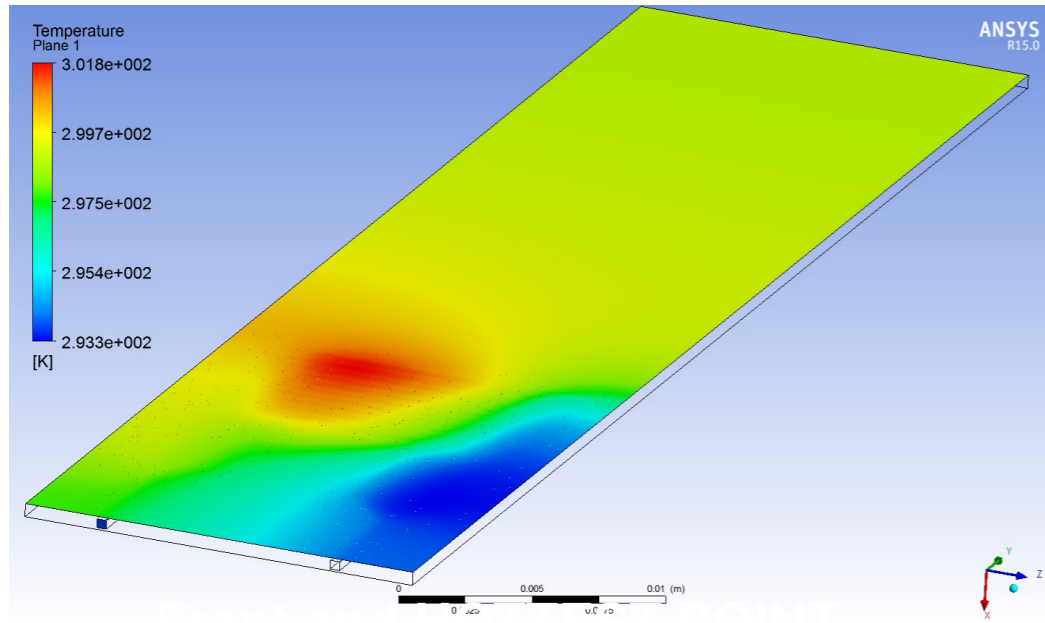


Good agreement with the **FE simulation** within 10%

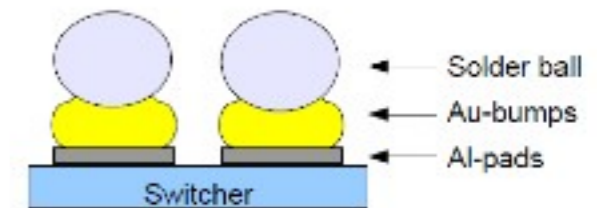
Measurement data errors

- $P \pm 1\%$ W
- $T \pm 1$ °C
- $\Delta T/\text{Power density} \pm 0,14$ °C/W
- flow $\pm 0,03$ l/h

Thermal simulations: MCC



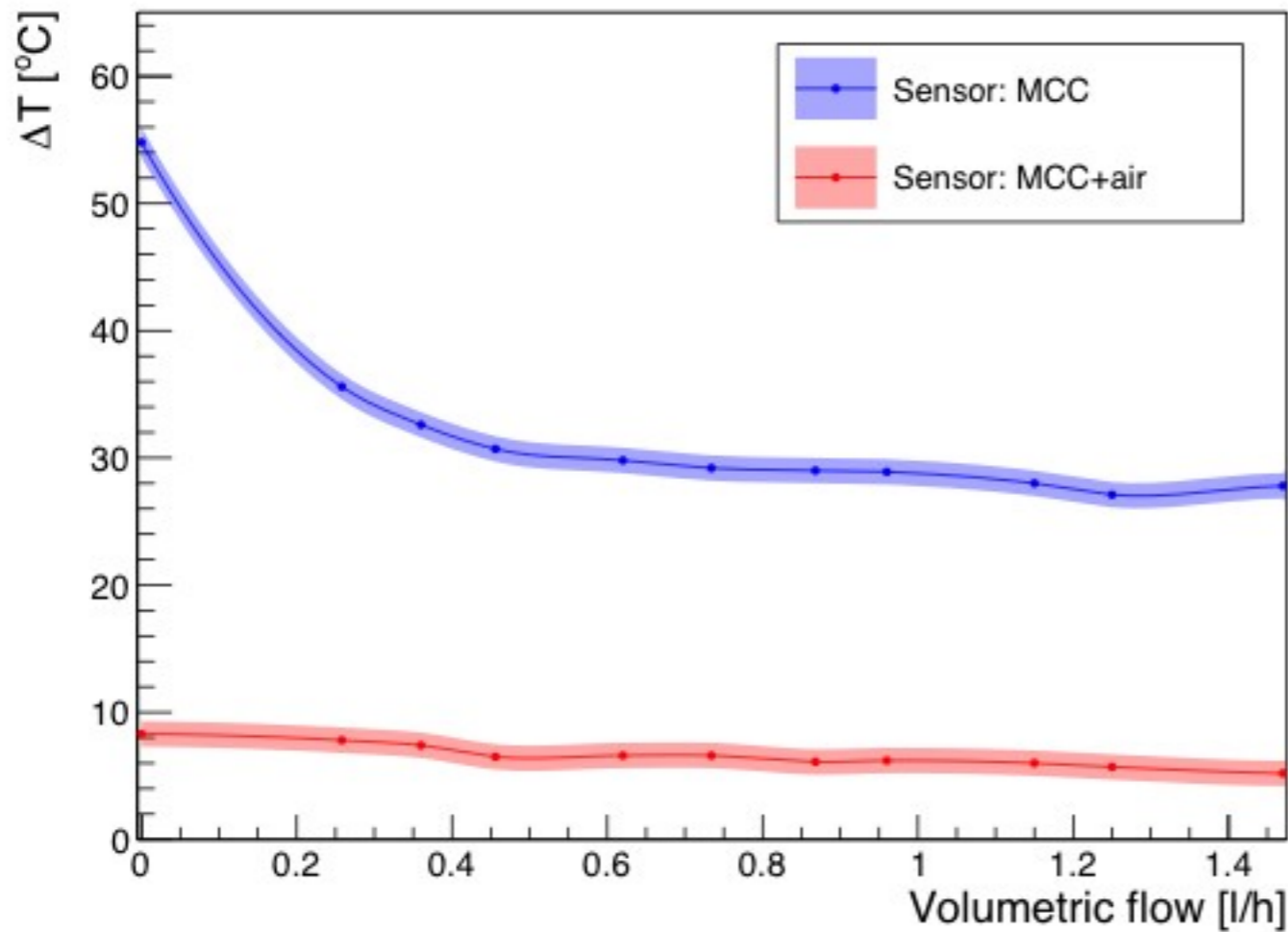
Realistic design
300 μm Si ASICS +
100 μm Bump-boundings
thermal resistivity of 6 W/m·K



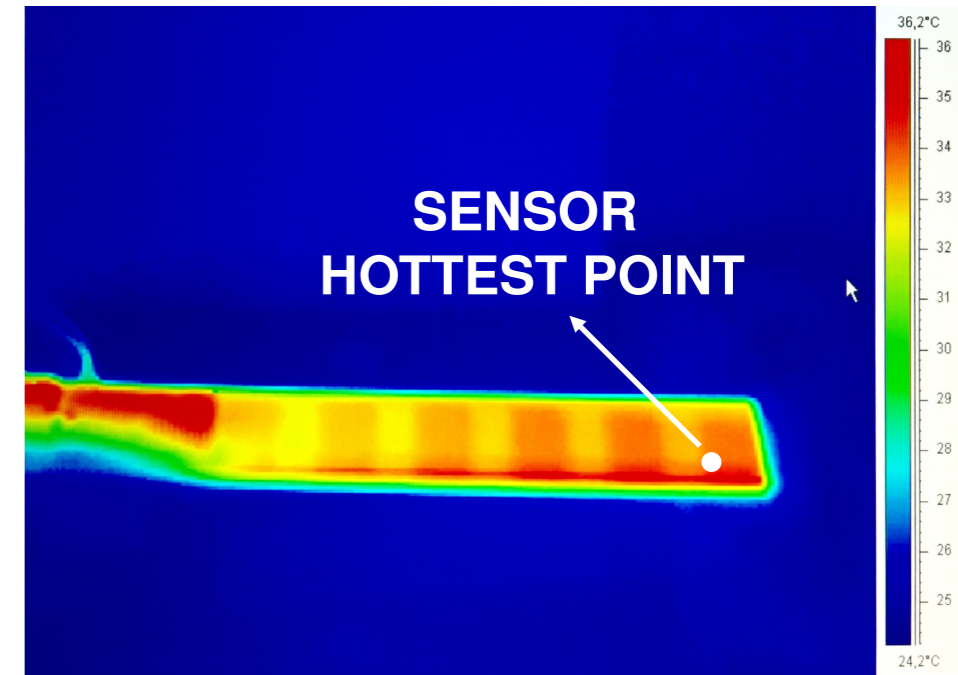
C.Mariñas PhD thesis [link](#)



Thermal measurements: MCC + air



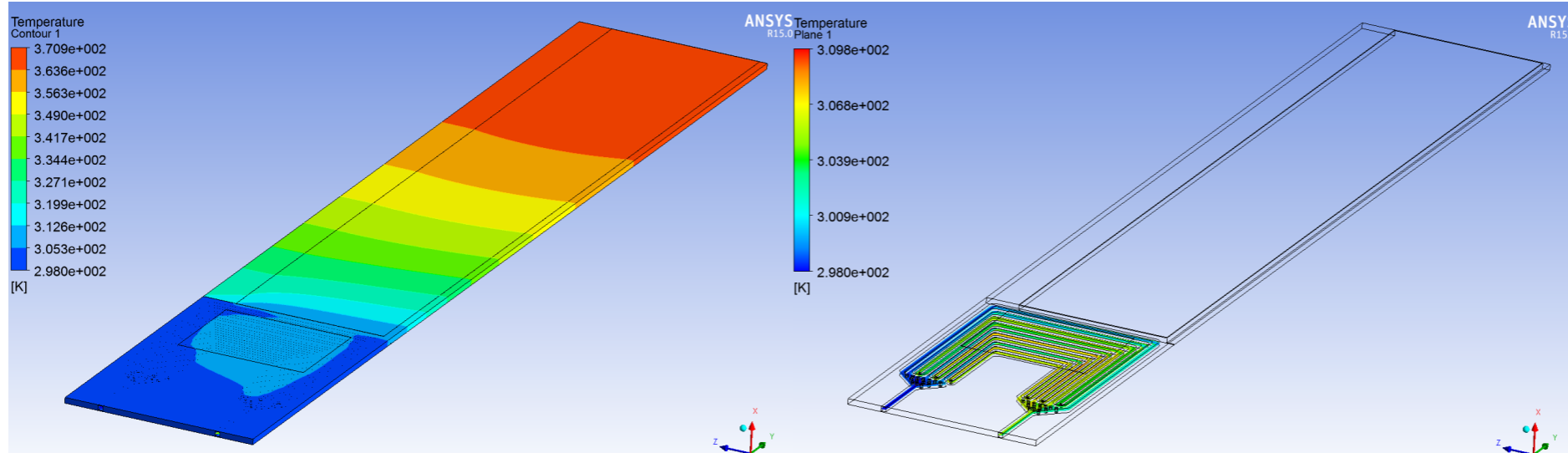
Cooling strategy: micro-channels running under the front end and gentle air flow on the sensor part



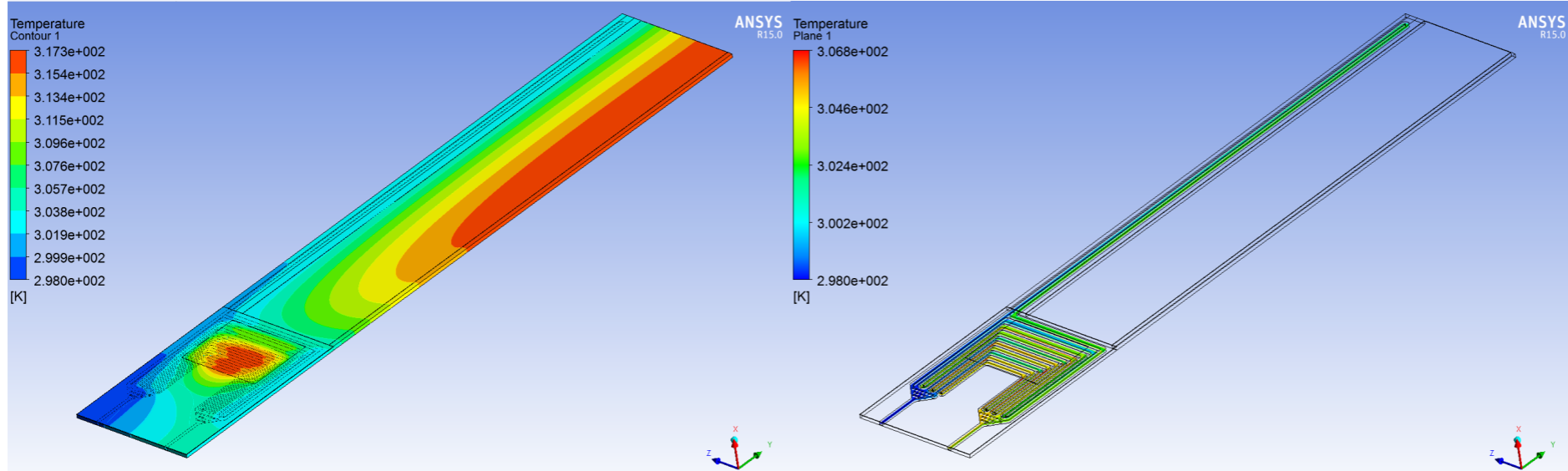
- Big difference between MCC and MCC+air at the sensor area hottest point
- Nearest regions to air input are efficiently cooled even with low air flow
- MCC has less impact in away points as expected and great cooling locally



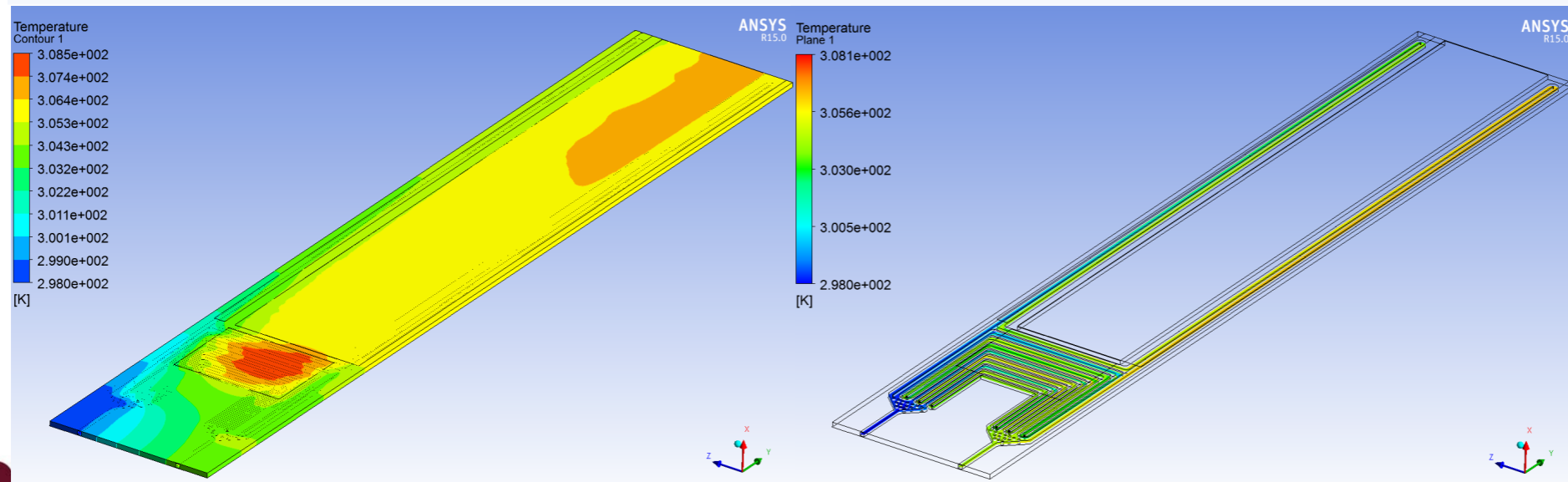
Thermal simulations: MCC Layouts



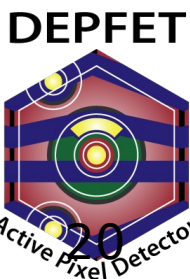
**Standard
MCC layout**
 $\Delta T = 73 \text{ K}$



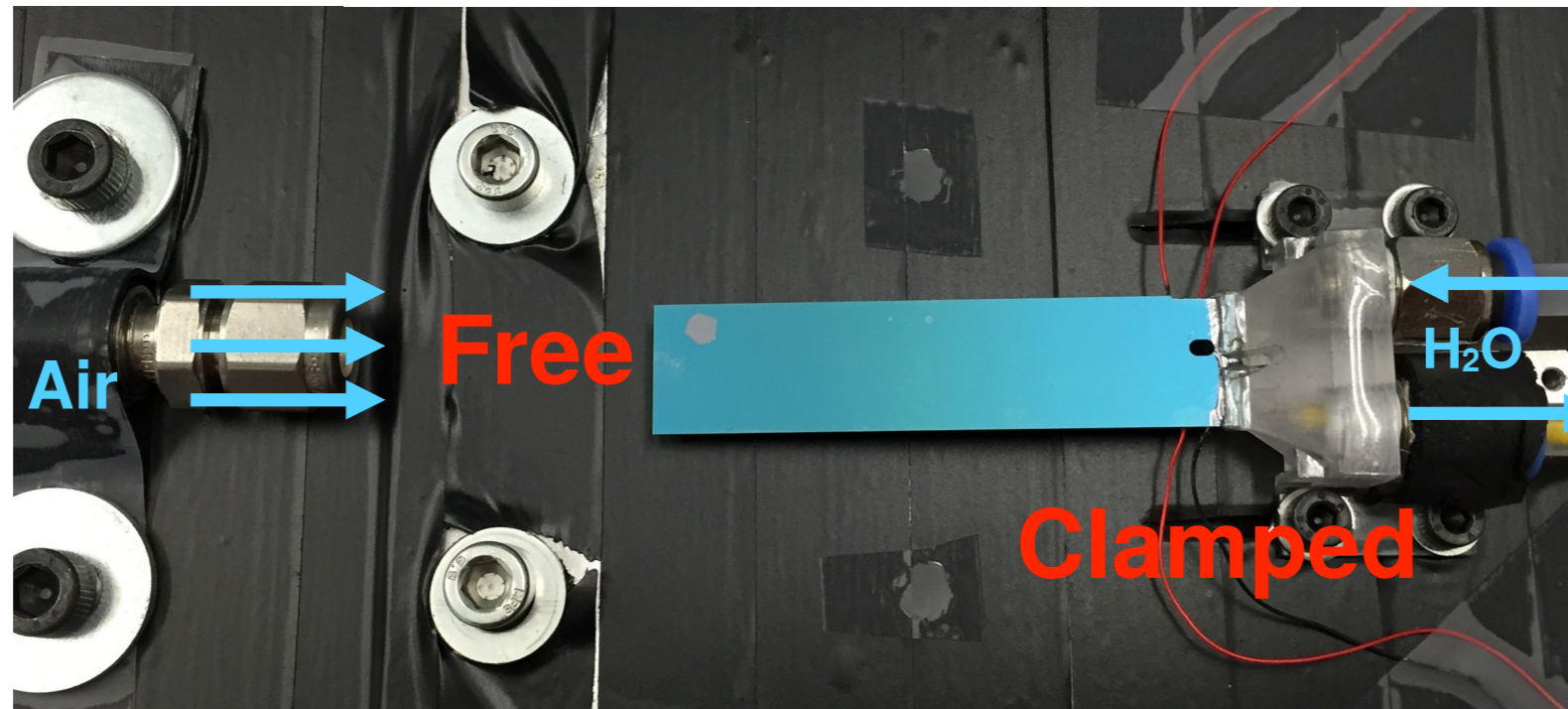
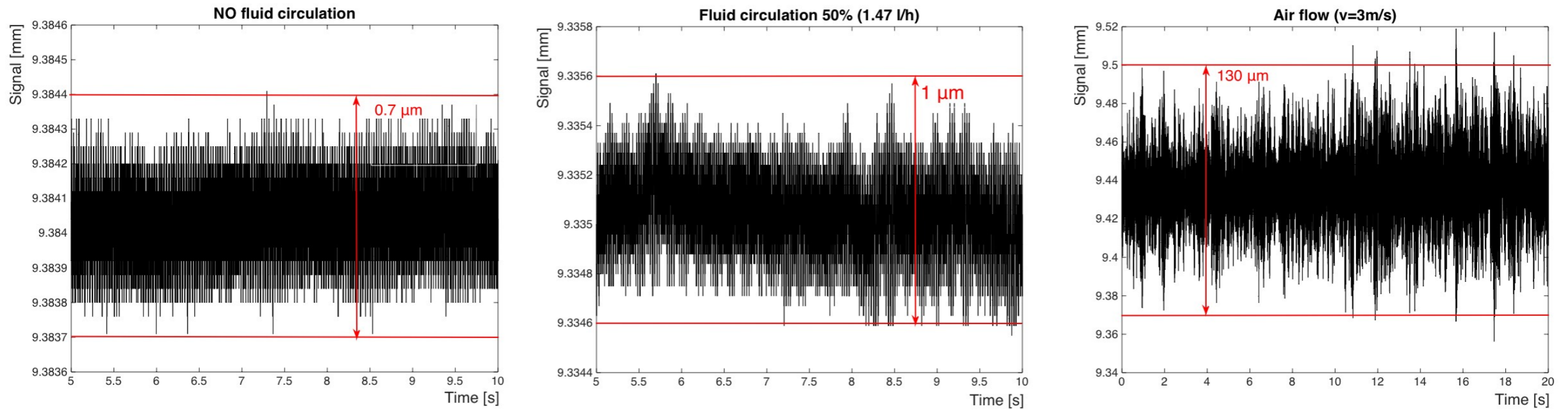
**Standard
MCC layout +
channel below
switchers**
 $\Delta T = 15 \text{ K}$



**Standard
MCC layout +
channel below
switchers +
channel in the
balcony**
 $\Delta T = 5 \text{ K}$

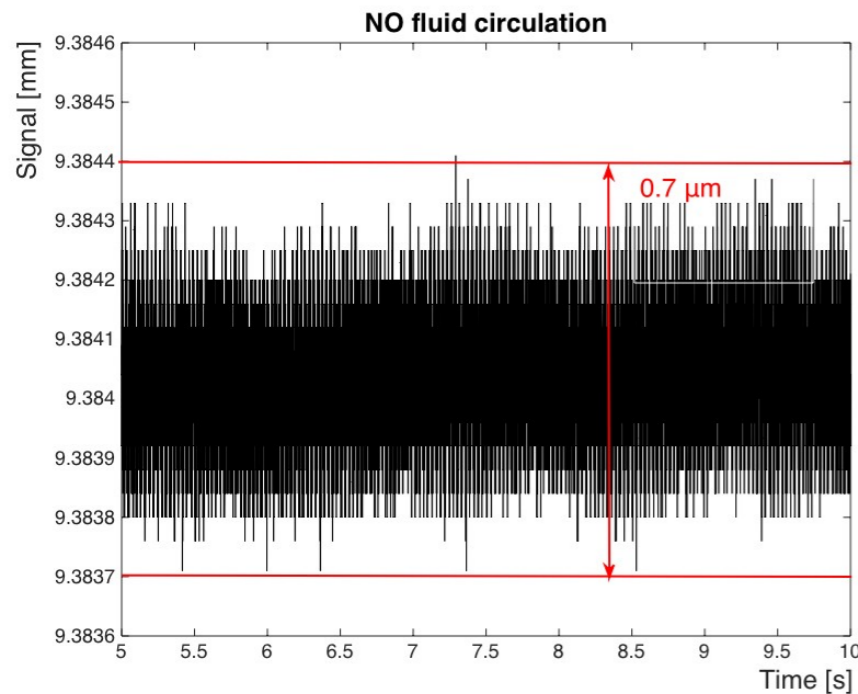


Vibrations and deformations



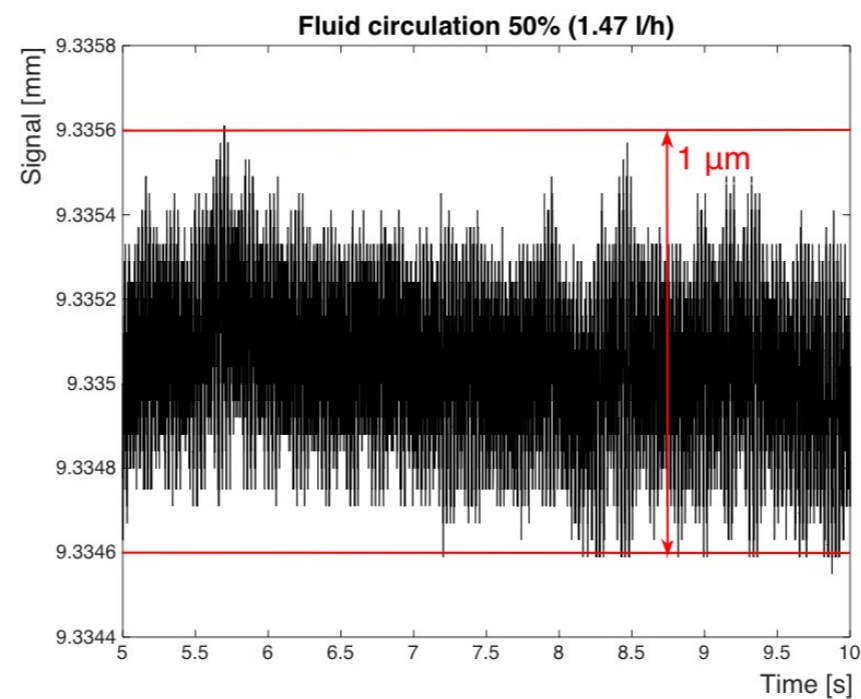
One extreme of the dummy is clamped to the 3D adaptor
→ amplifies vibrations

Vibrations and deformations



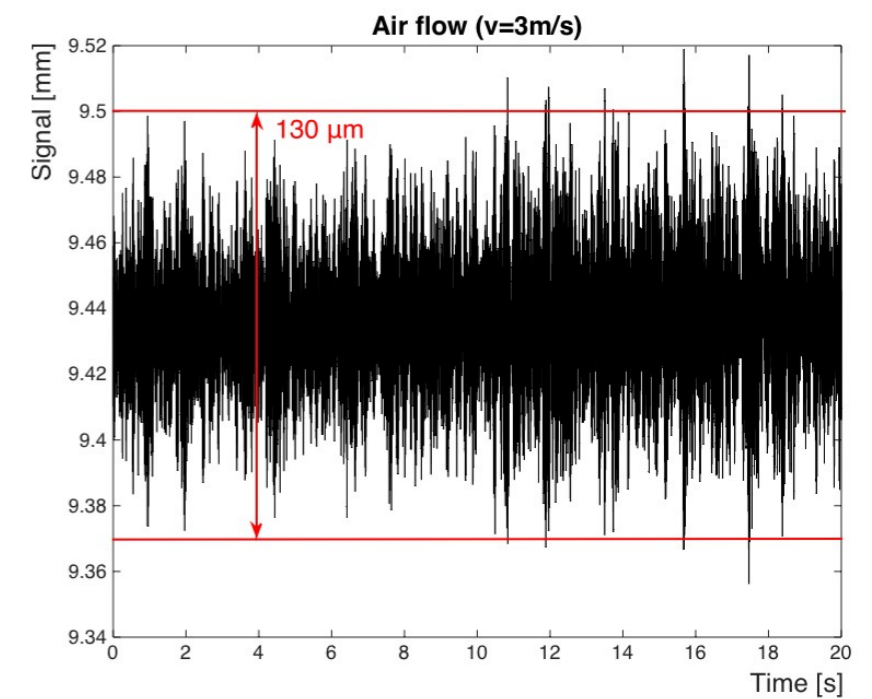
**No fluid circulation
and no air flowing**

Peak to peak of the
signal $\sim 0,7 \mu\text{m}$
RMS $\sim 0,3 \mu\text{m}$



**Fluid circulation
1,47 l/h**

Peak to peak of the
signal $\sim 0,1 \mu\text{m}$
RMS $\sim 0,4 \mu\text{m}$



**Air flowing
3 m/s**

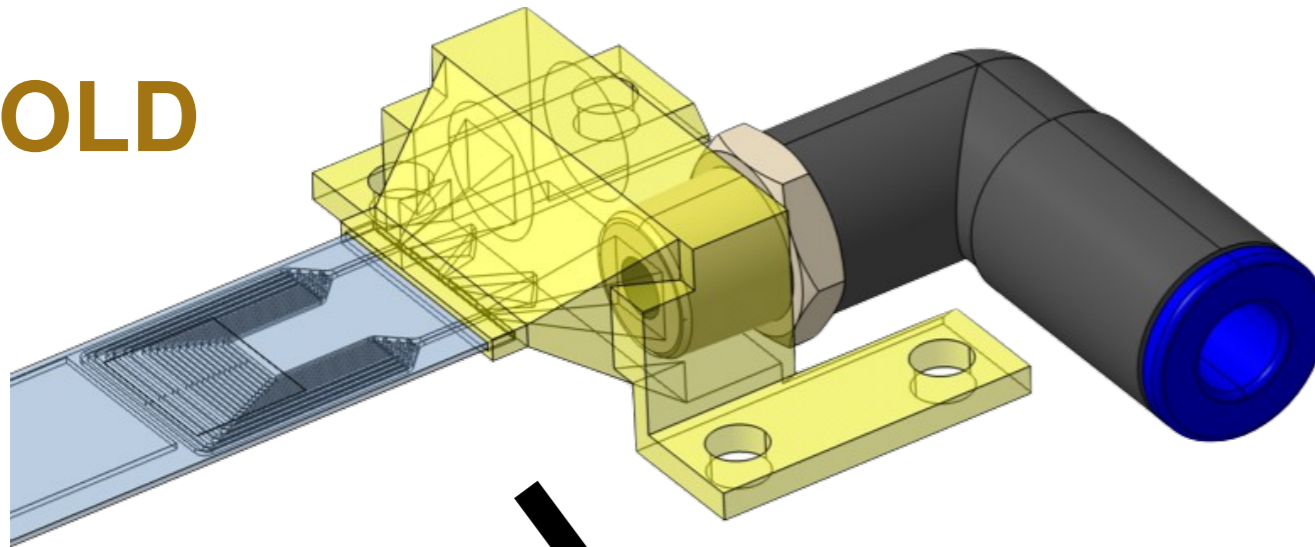
Peak to peak of the
signal $\sim 130 \mu\text{m}$
RMS $\sim 57 \mu\text{m}$

MCC has no significant impact on mechanical stability

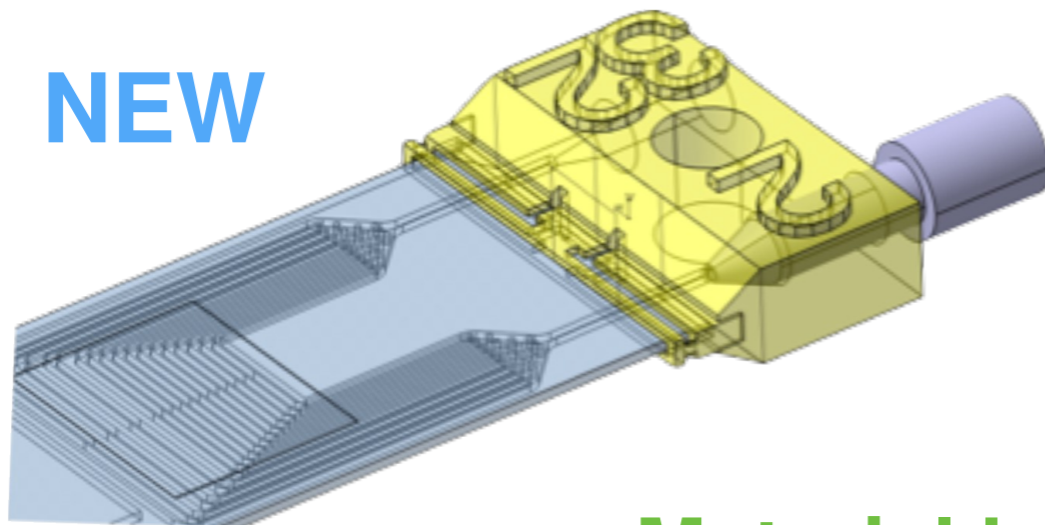


Towards a low mass interconnection

OLD

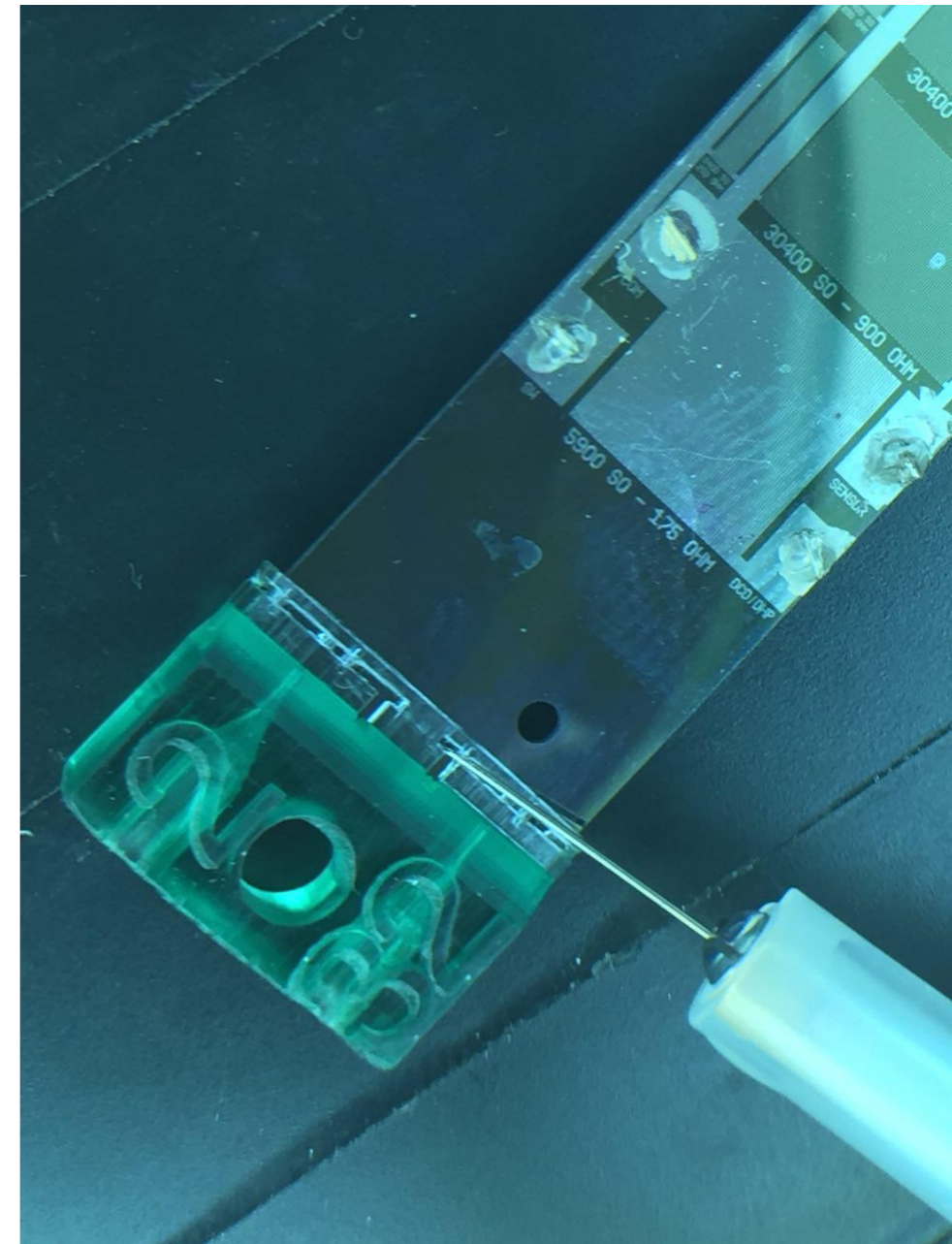


NEW



Peek tube

Peek to Swagelok connector



Material budget is reduced a factor ~ 4
1.5% X0 Still largely driven by connector



Conclusions

Measurements on mock-up and mechanical samples confirm that the combination power pulsing + air cooling can be made to work if care is taken to limit the air flow to several m/s

To be done: impact of the B-field, long term stability, viable way to set up air flow

For localized power dissipation, **up to many W/cm^2** with, a minimalistic micro-channel cooling (mono-phase, low pressure) can provide excellent control and a modest temperature increase ($10^\circ C$)

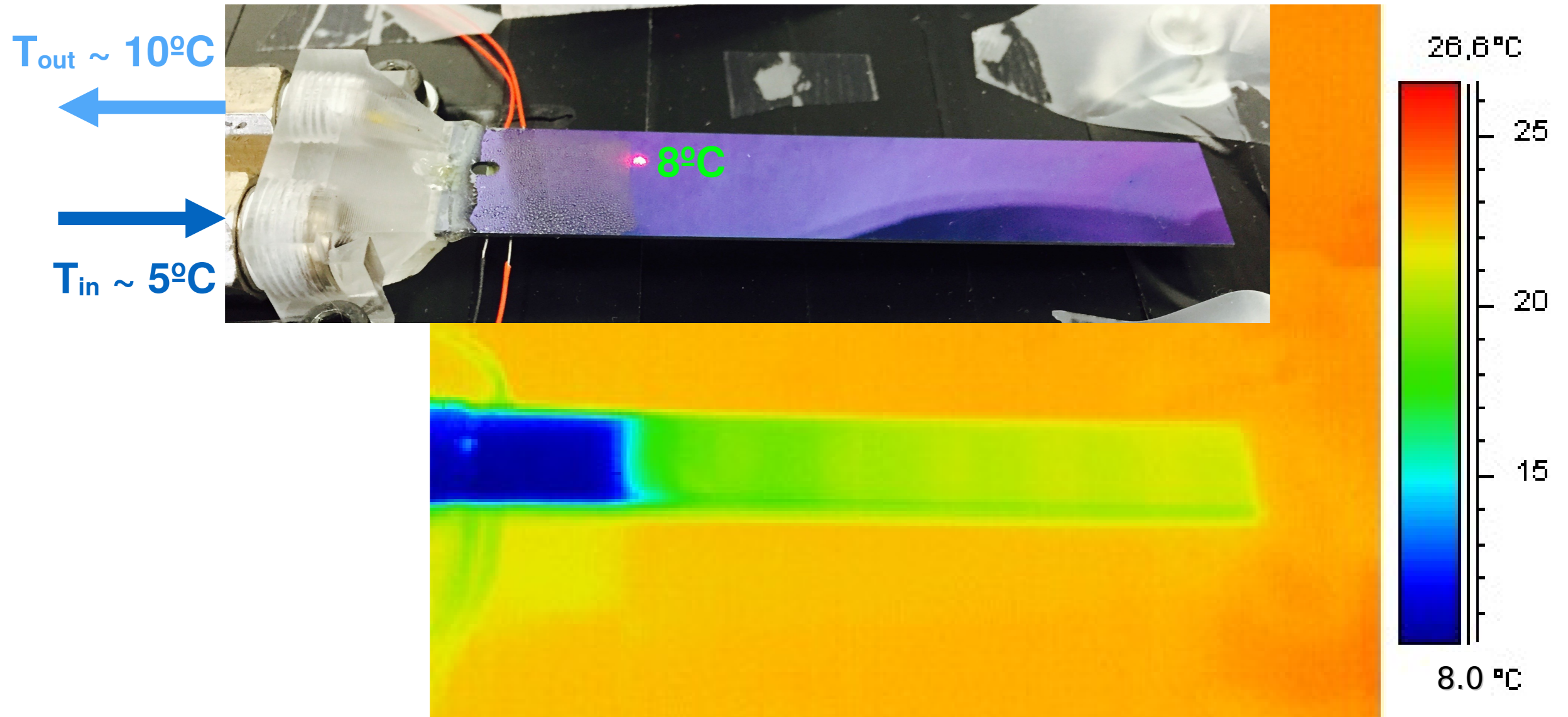
To be done: miniature connector



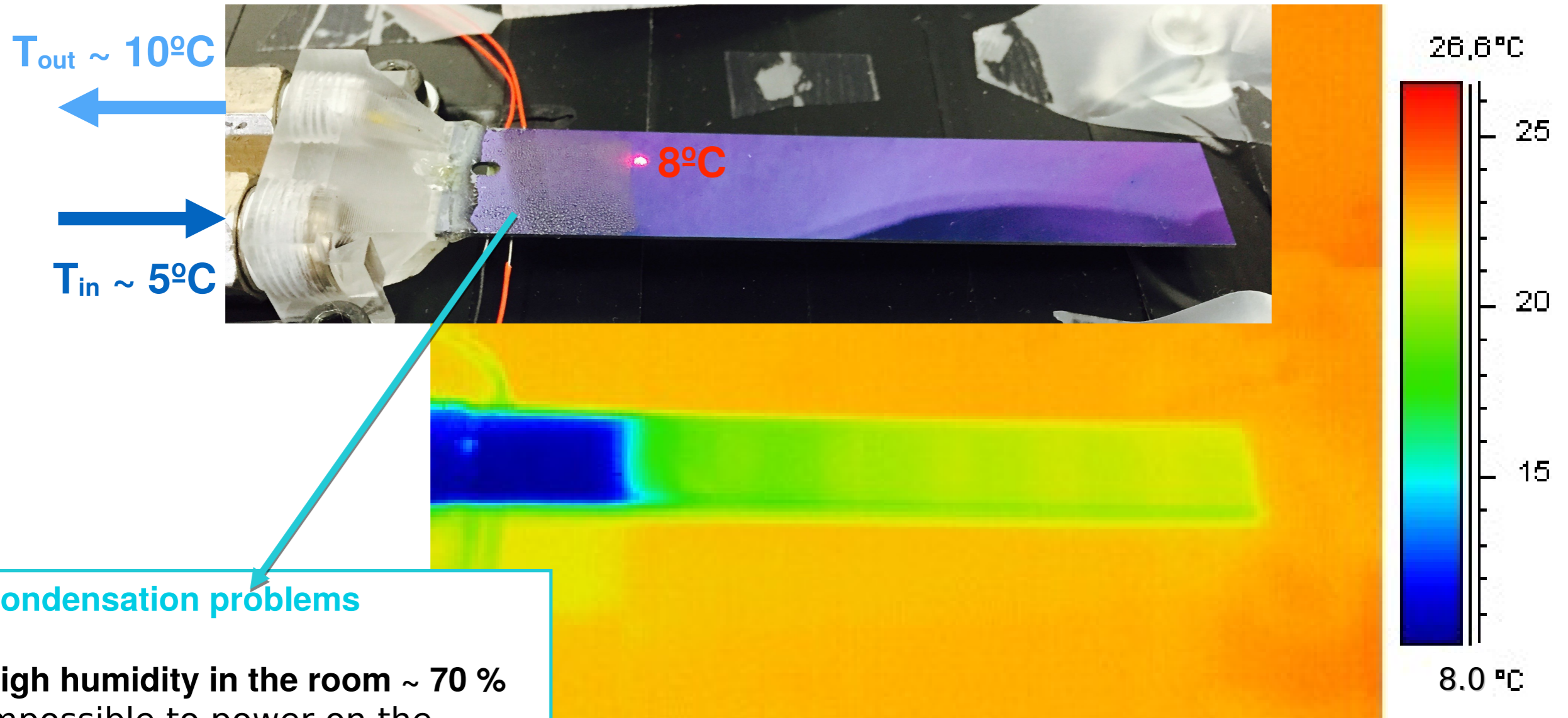
The background features a dark, textured surface with a grid of glowing, cylindrical shapes. A diagonal line runs from the top-left towards the bottom-right. The text "Thank you for your attention" is centered in a bold, blue font.

Thank you for your attention

Thermal measurements: cold water



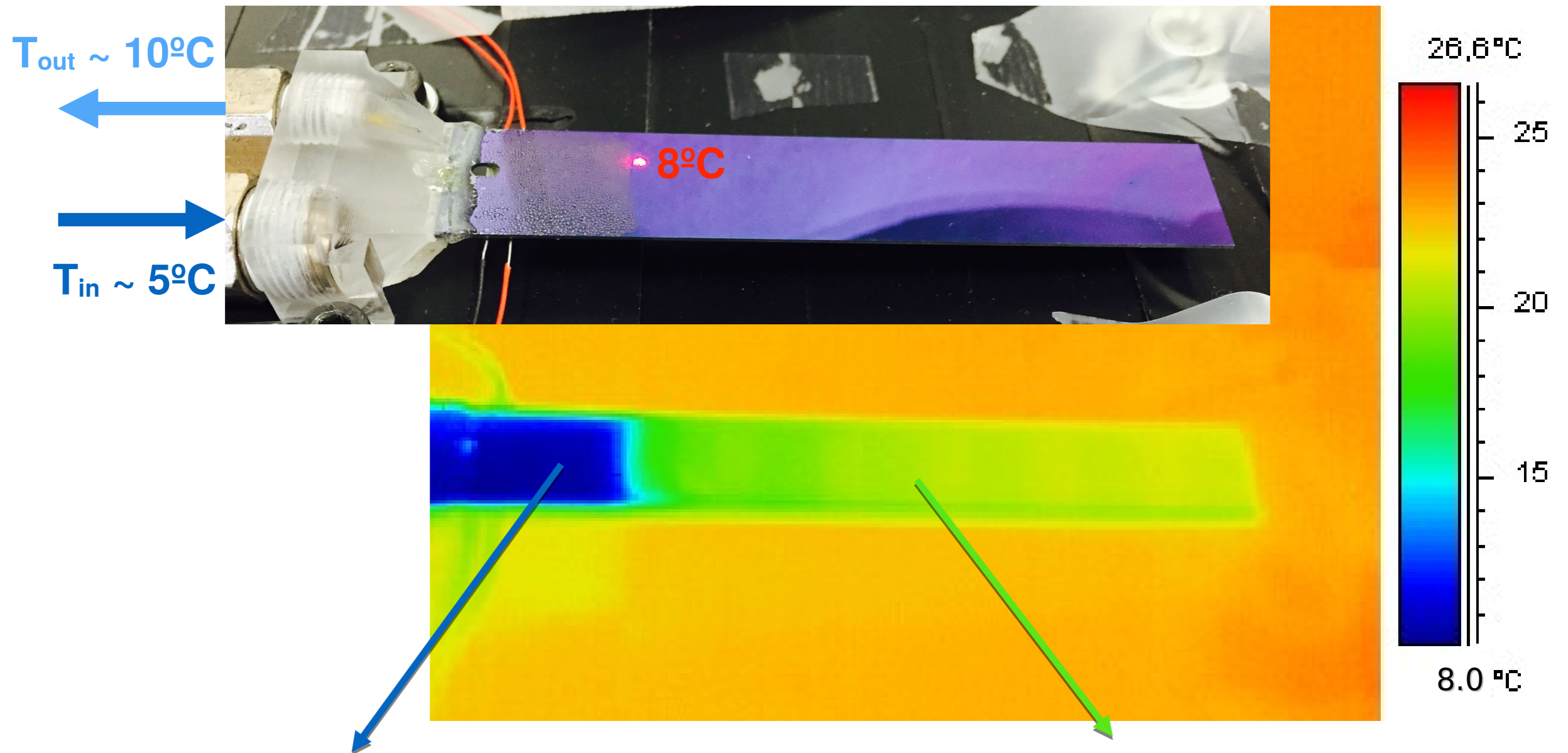
Thermal measurements: cold water



Condensation problems

High humidity in the room $\sim 70\%$ impossible to power on the aluminum resistances (possible **short-circuit** due to the water on the soldering)

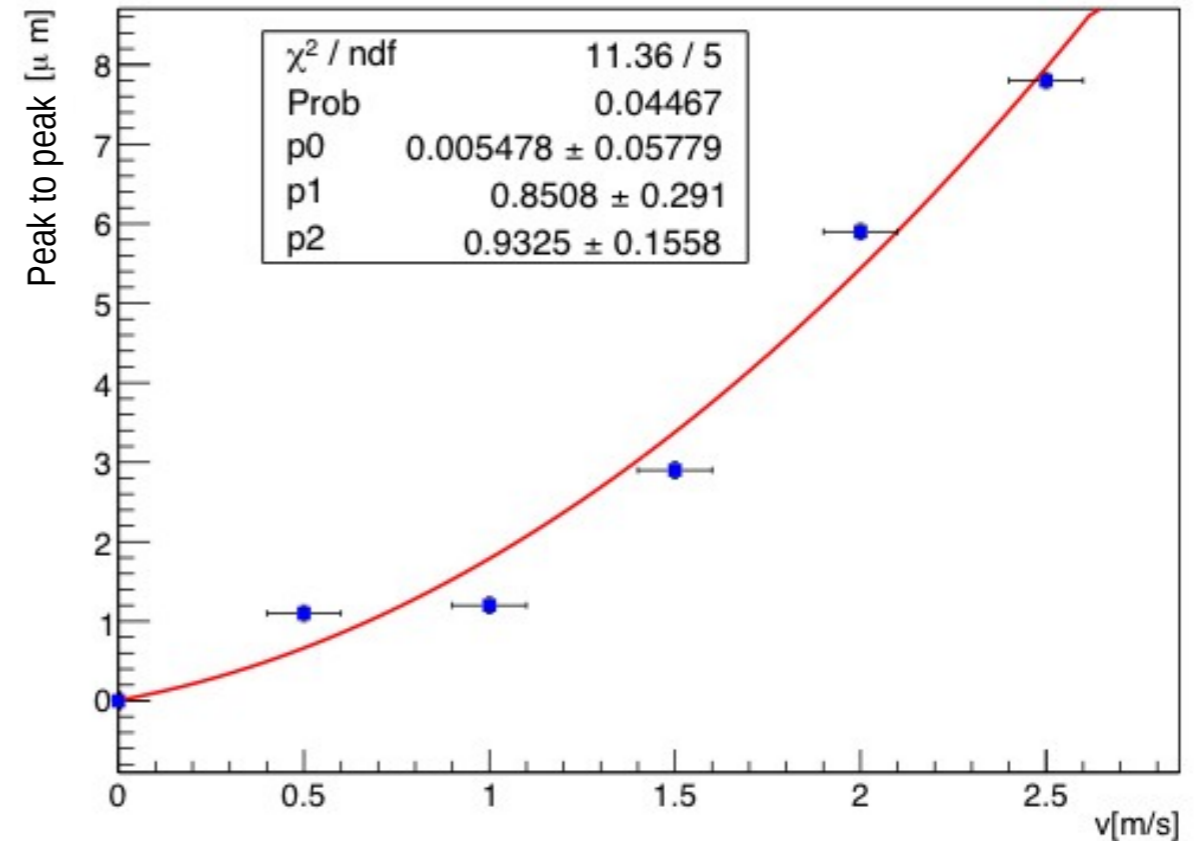
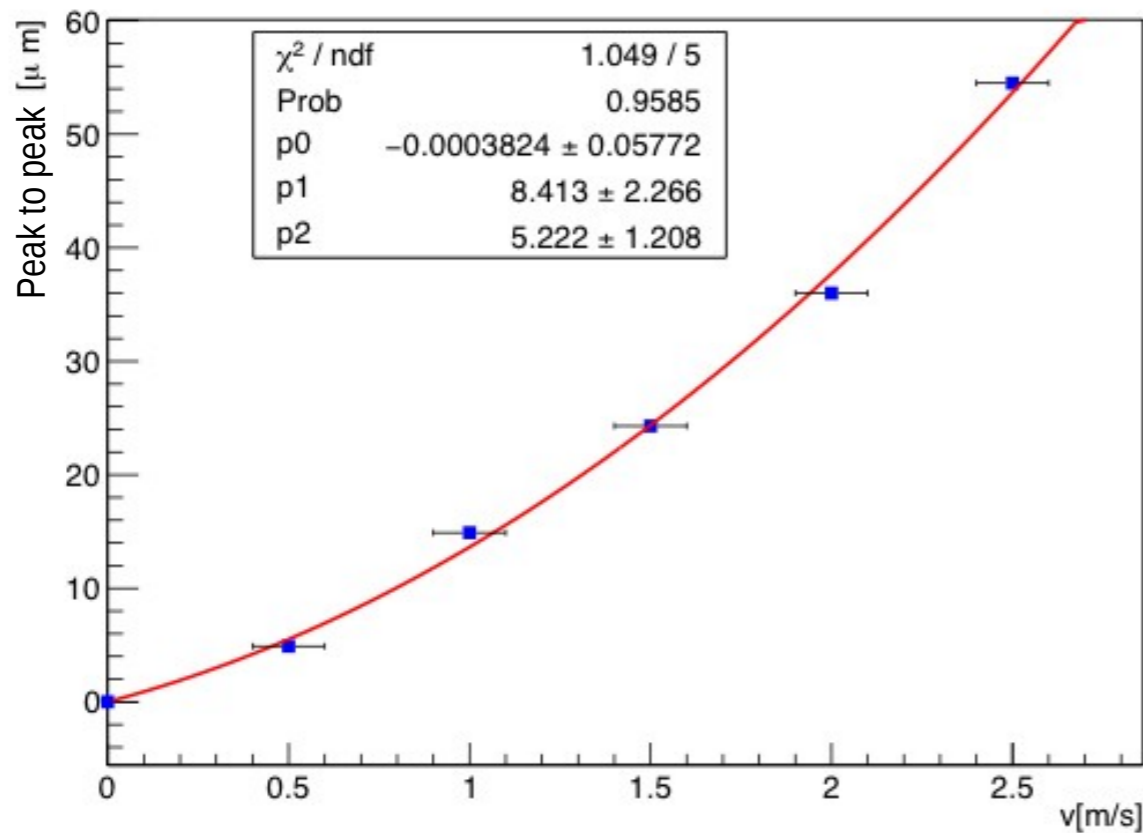
Thermal measurements: cold water



MCC region is cooled
 18°C below T_{Room}

In this region the effect of the MCC is
quite less pronounced $5-10^{\circ}\text{C}$ below

Amplitude vs v_{air}

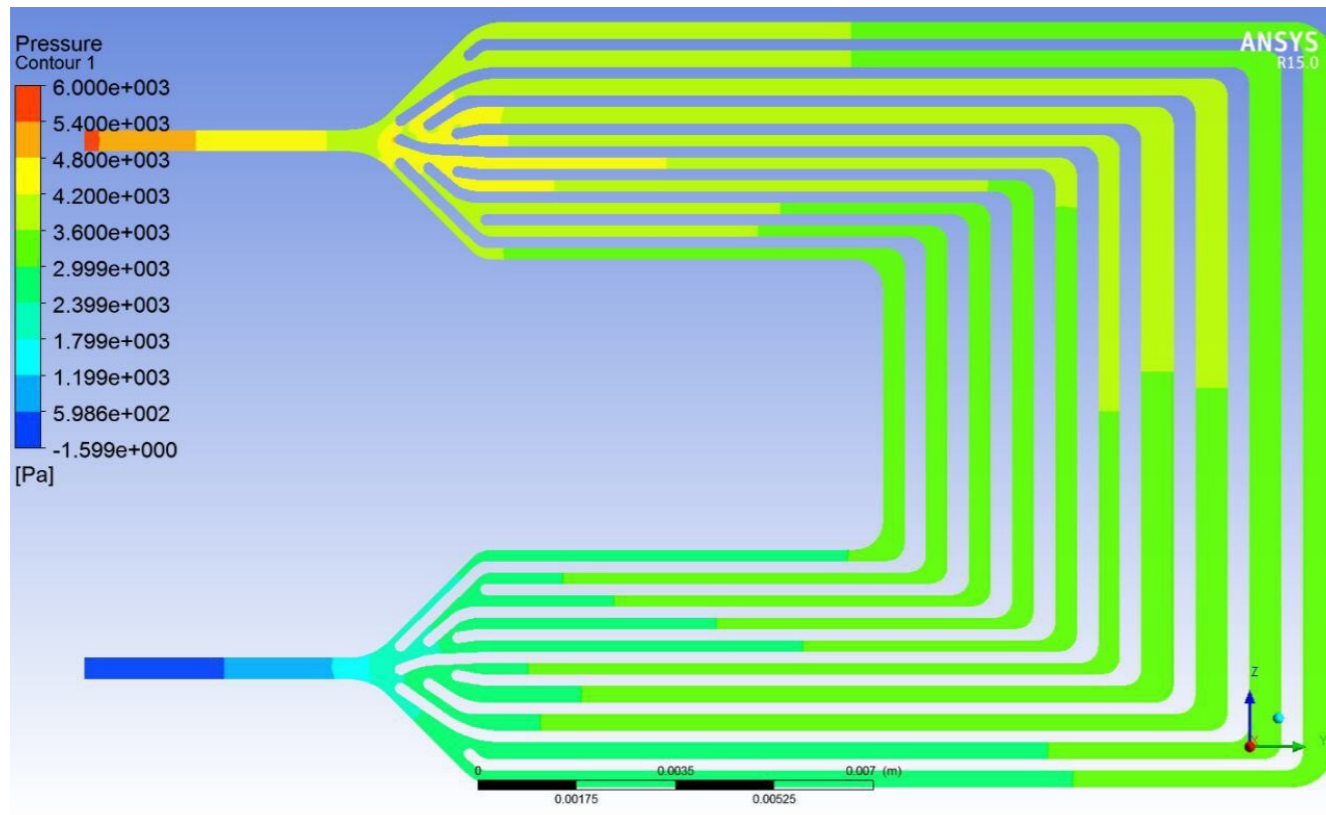


Clamped-Free

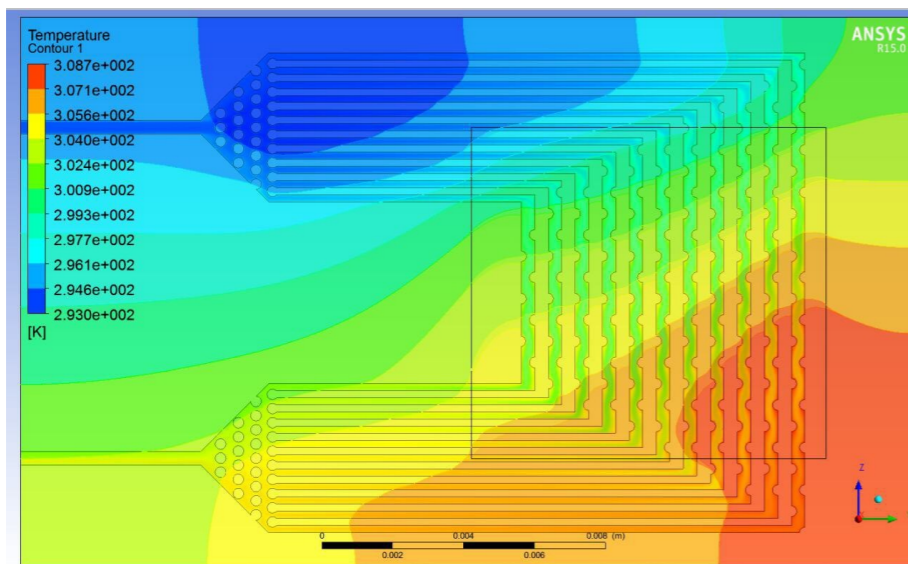
Clamped-Clamped

- Peak-to-peak amplitude is the change between peak (highest amplitude value) and trough (lowest amplitude value)
- $\text{RMS} \approx (\text{PeaktoPeak}/2) * 0.707$ (approximation)
- For $v = 2.5 \text{ m/s}$ the amplitude of vibration is:
 - $\sim 19 \mu\text{m}$ for **clamped-free** configuration
 - $\sim 2.8 \mu\text{m}$ for **clamped-clamped** configuration

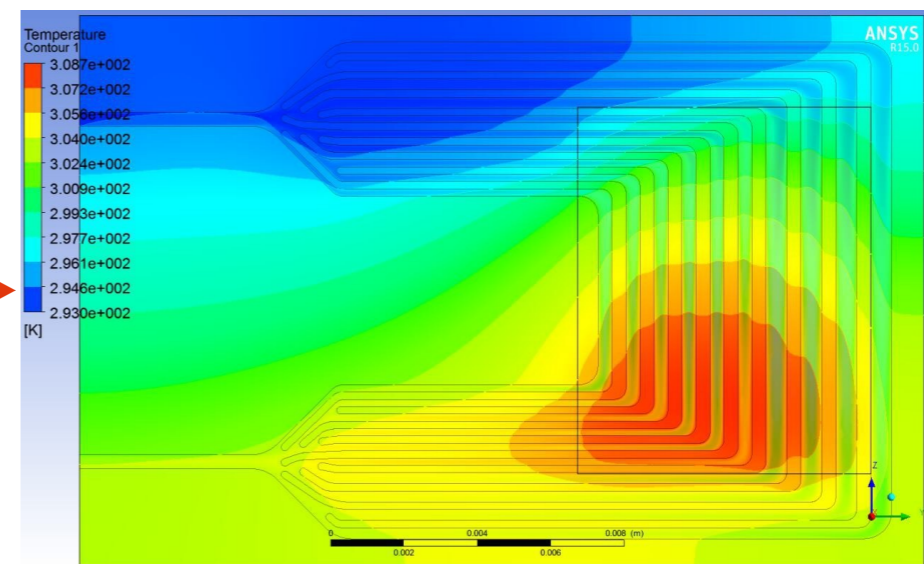
Optimized MCC geometry



- More homogenous flow
- Reduce pressure gradients
- Minimize and confine the heat spread



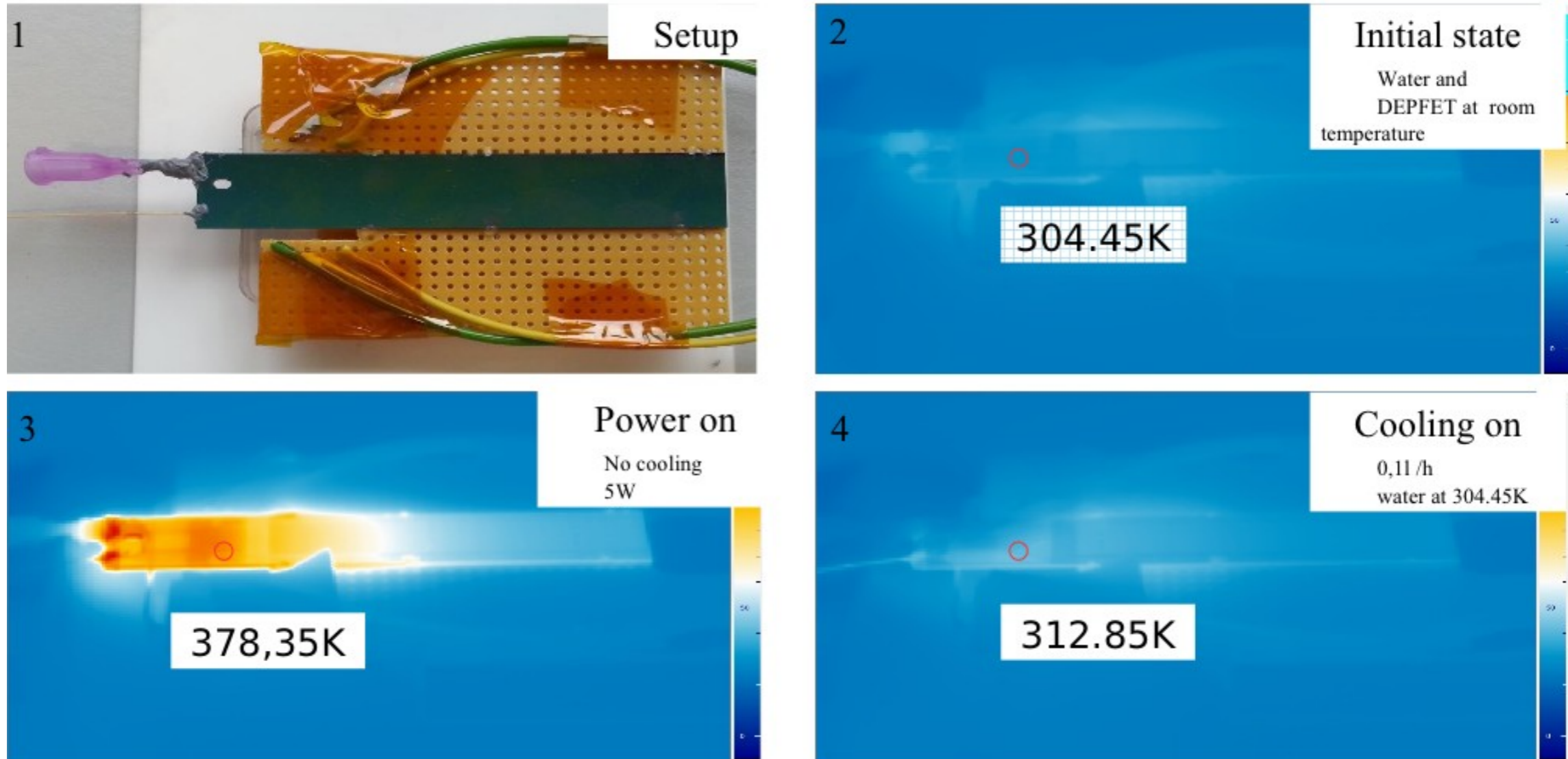
Recent geometry



Optimized geometry

Micro-channel Cooling

Tests made: 5W and water cooling

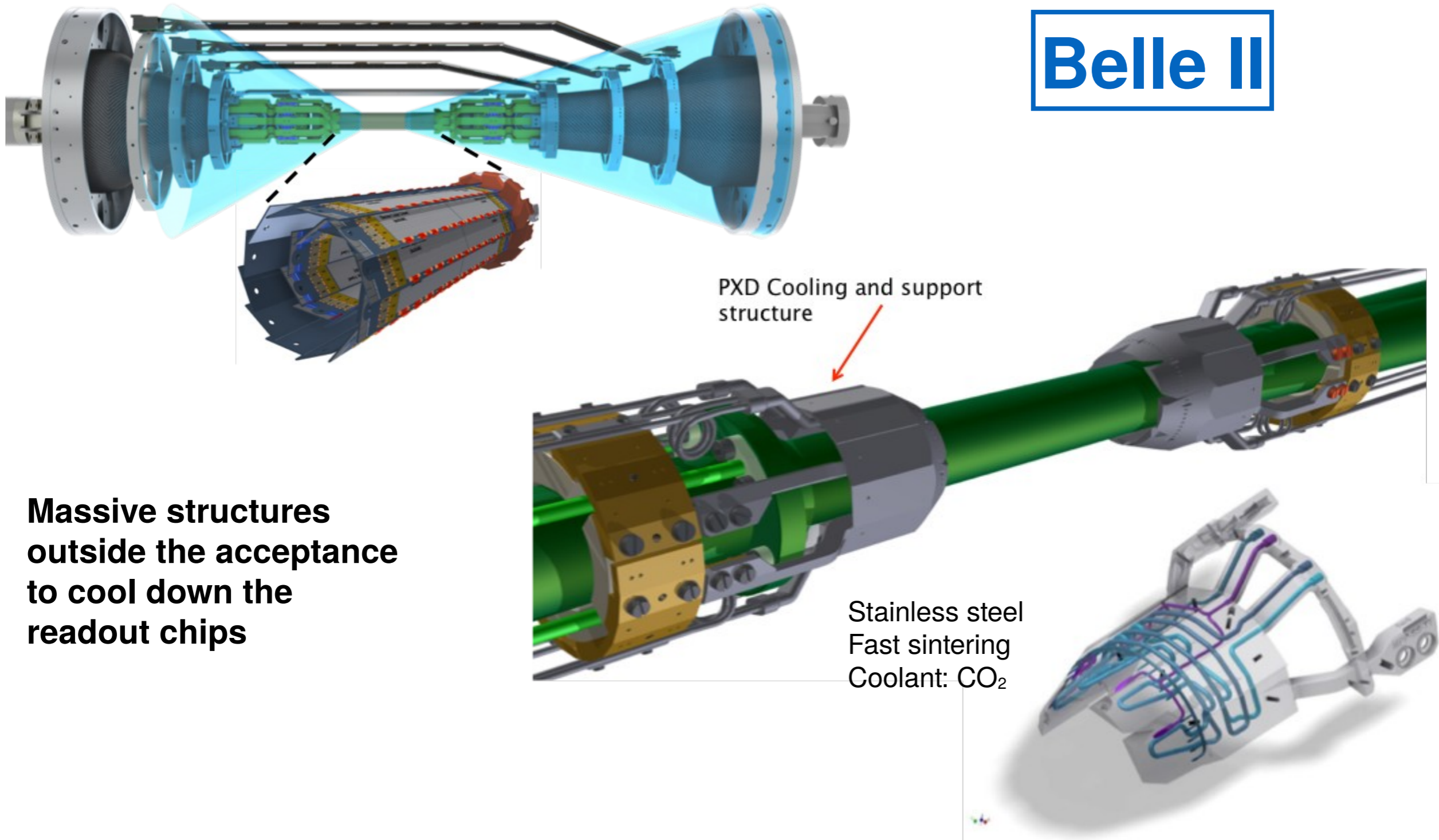


As shown first measurements, MCC with a flow of 0.1 l/h offers promising results

LCWS 2014 Belgrade: <https://agenda.linearcollider.org/event/6389/session/4/contribution/172/material/slides/0.pdf>

Cooling strategies

Belle II



**Massive structures
outside the acceptance
to cool down the
readout chips**